

EE 330

Lecture 18

- P-channel Modeling
- Relationship Between Switch-Level and Higher Level Models
- CMOS Process Flow

For those that choose to participate in class real-time virtually, please use the Zoom link

[Zoom Virtual Class Participation](#)

Office Hours via Zoom Spring 2022: Tuesday, Thursday, and Friday 11:15-noon or by appointment [Zoom Office Hours Link](#)

<https://iastate.zoom.us/j/92142125293>

Prelab Announcement

A Pre-Lab will be posted on Canvas for Lab 7

Exam Schedule

Exam 2 will be given on Friday March 11

Exam 3 will be given on Friday April 15

Photo courtesy of the director of the National Institute of Health (NIH)



As a courtesy to fellow classmates, TAs, and the instructor

Wearing of masks during lectures and in the laboratories for this course would be appreciated irrespective of vaccination status

How many models of the MOSFET do we have?

Switch-level model (2)

Square-law model

Square-law model (with λ and bulk additions)

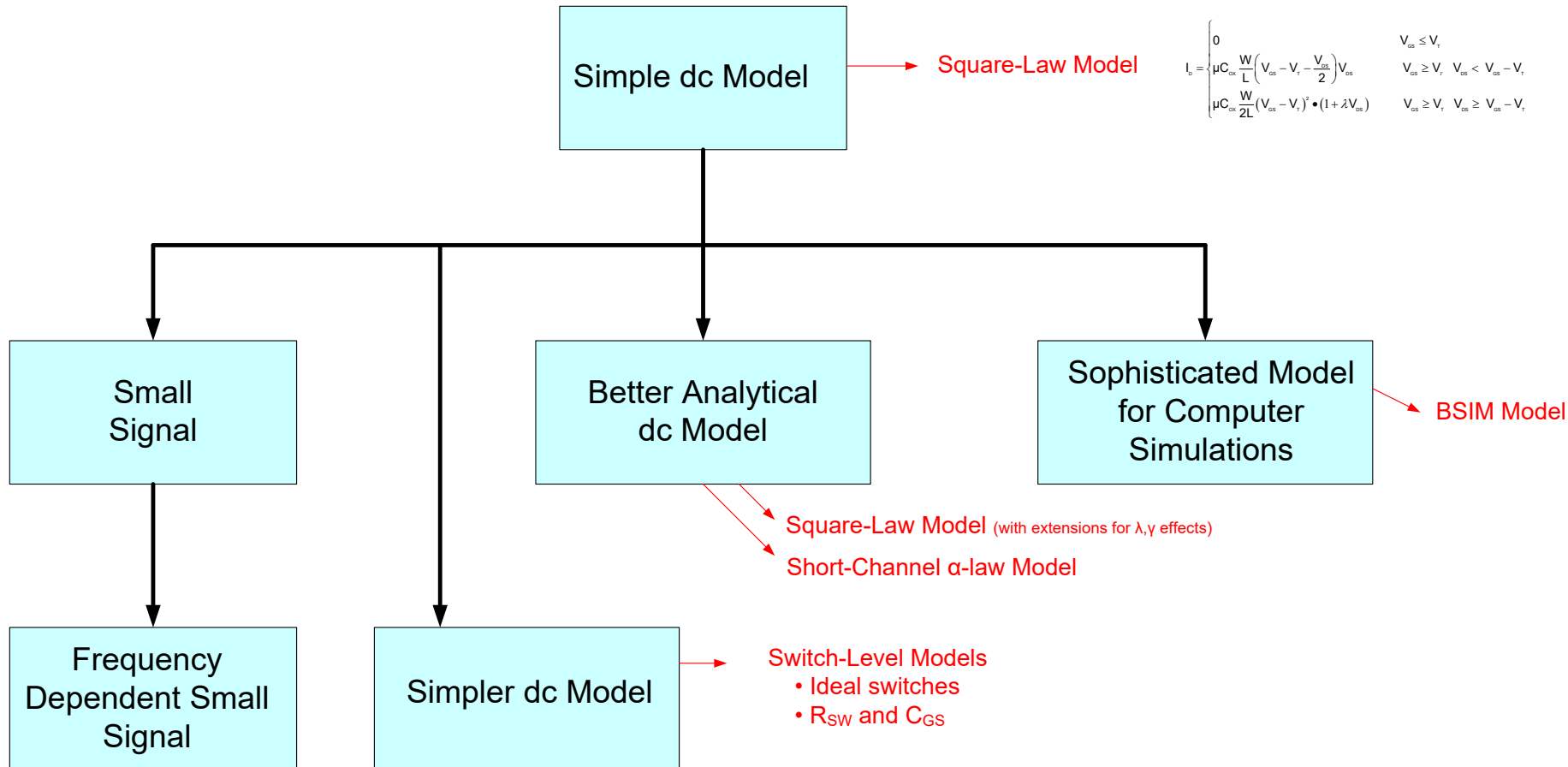
α -law model (with λ and bulk additions)

BSIM model

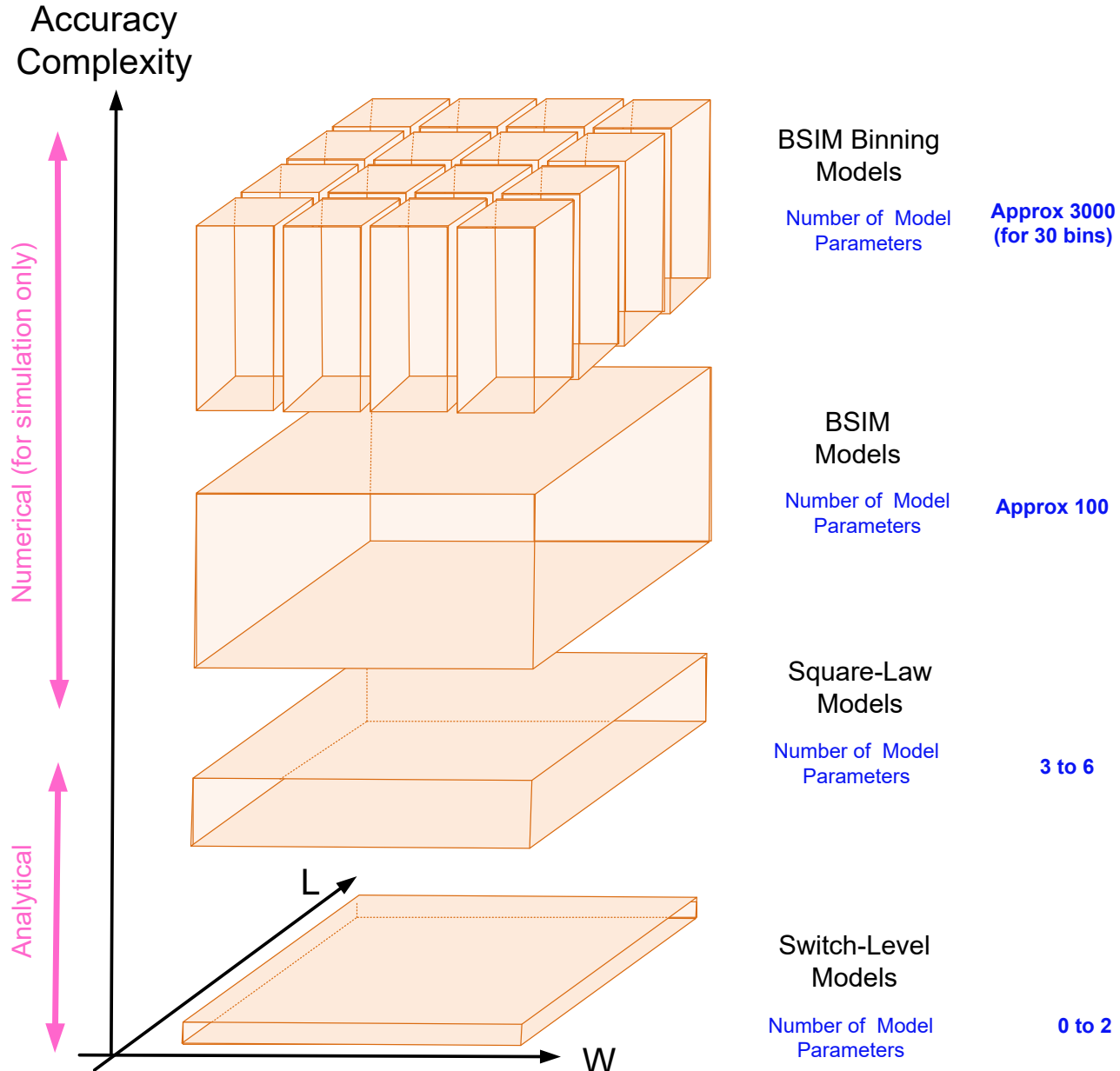
BSIM model (with binning extensions)

BSIM model (with binning extensions and process corners)

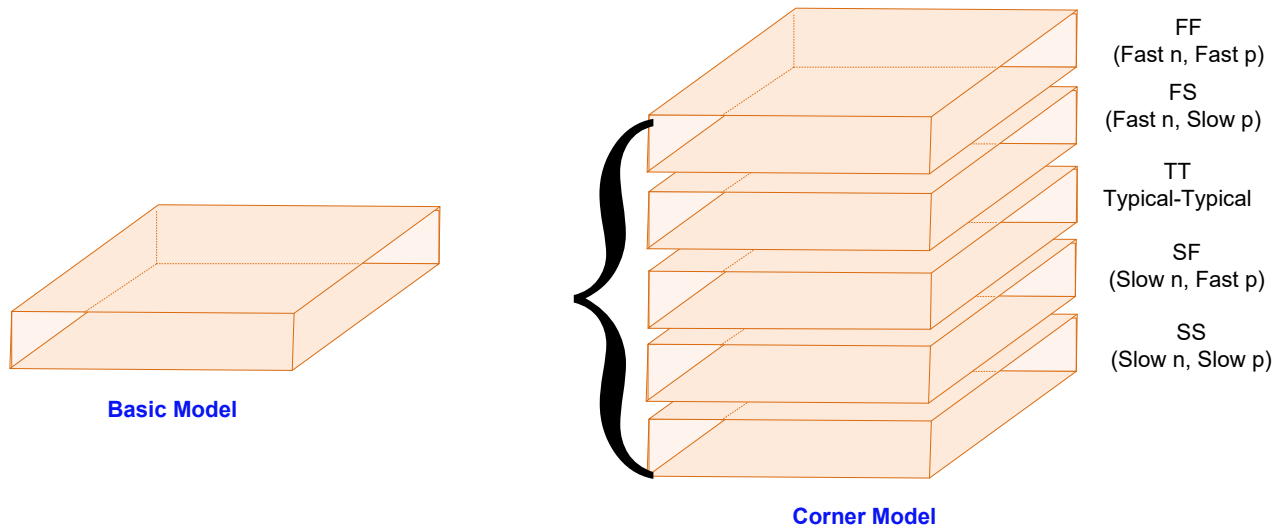
Model Status



Hierarchical Model Comparisons



Corner Models



Applicable at any level in model hierarchy (same model, different parameters)

Often 4 corners (FF, FS, SF, SS) used but sometimes many more

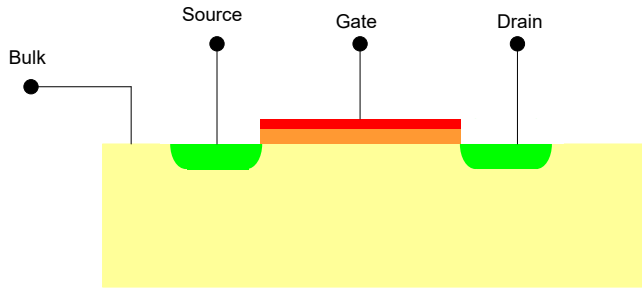
Designers must provide enough robustness so good yield at all corners

Relationship between N-channel and P-channel models

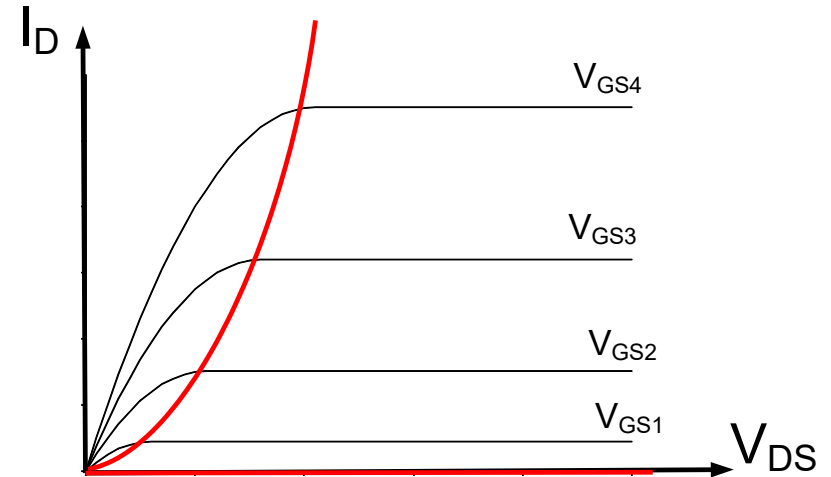
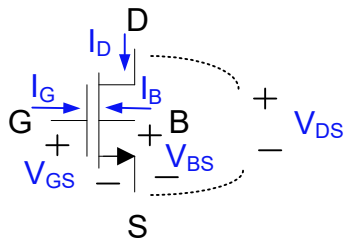
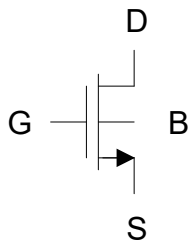
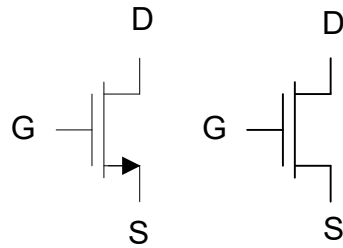
Basic models for n-channel and p-channel models are the same

Major difference is in values for model parameters and direction of electrical port variables

n-channel p-channel modeling



n-channel MOSFET



$$V_{GS4} > V_{GS3} > V_{GS2} > V_{GS1} > 0$$

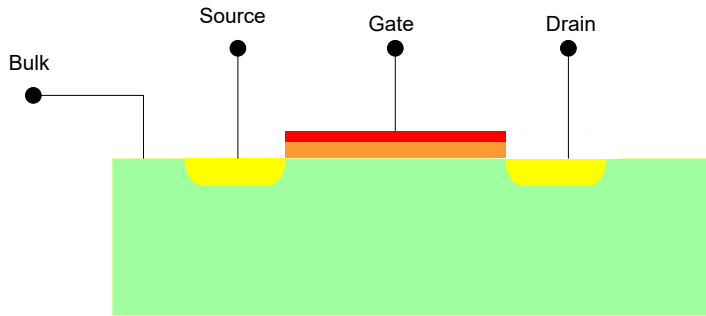
(for enhancement devices)

$$I_D = \begin{cases} 0 & V_{GS} \leq V_{Tn} \\ \mu_n C_{ox} \frac{W}{L} \left(V_{GS} - V_{Tn} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \geq V_{Tn}, V_{DS} < V_{GS} - V_{Tn} \\ \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_{Tn})^2 & V_{GS} \geq V_{Tn}, V_{DS} \geq V_{GS} - V_{Tn} \end{cases}$$

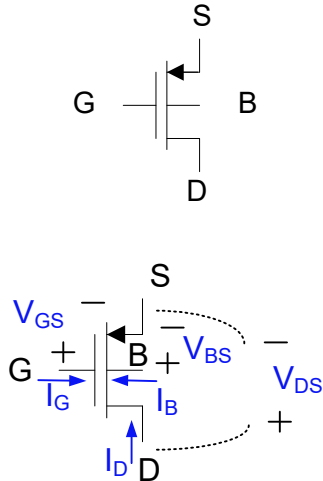
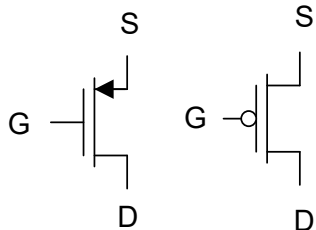
$I_G = I_B = 0$

Positive V_{DS} and V_{GS} cause a positive I_D

n-channel p-channel modeling

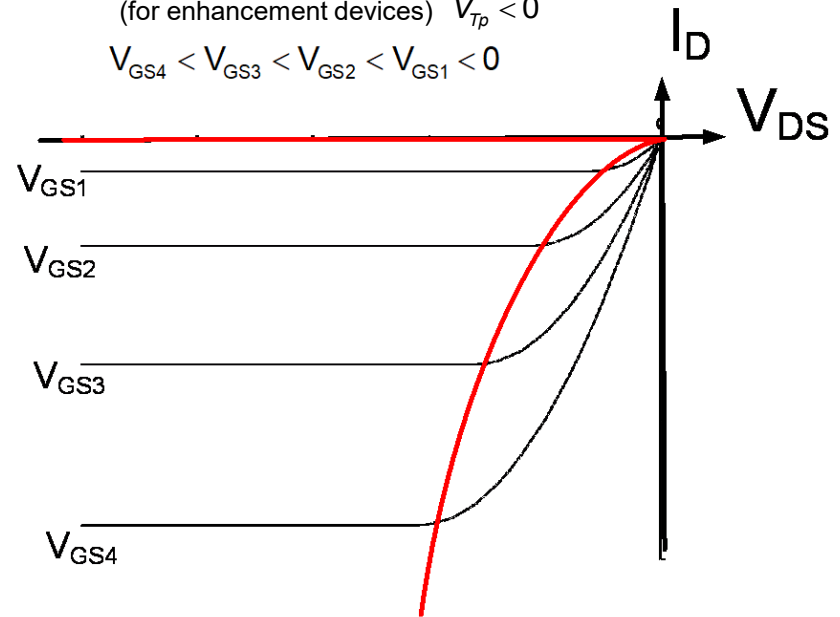


p-channel MOSFET



(for enhancement devices) $V_{Tp} < 0$

$V_{GS4} < V_{GS3} < V_{GS2} < V_{GS1} < 0$



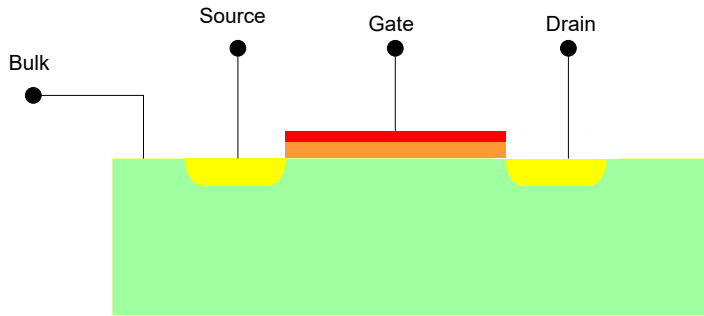
$$I_D = \begin{cases} 0 & V_{GS} \geq V_{Tp} \\ -\mu_p C_{ox} \frac{W}{L} \left(V_{GS} - V_{Tp} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \leq V_{Tp} \quad V_{DS} > V_{GS} - V_{Tp} \\ -\mu_p C_{ox} \frac{W}{2L} (V_{GS} - V_{Tp})^2 & V_{GS} \leq V_{Tp} \quad V_{DS} \leq V_{GS} - V_{Tp} \end{cases}$$

$I_G = I_B = 0$

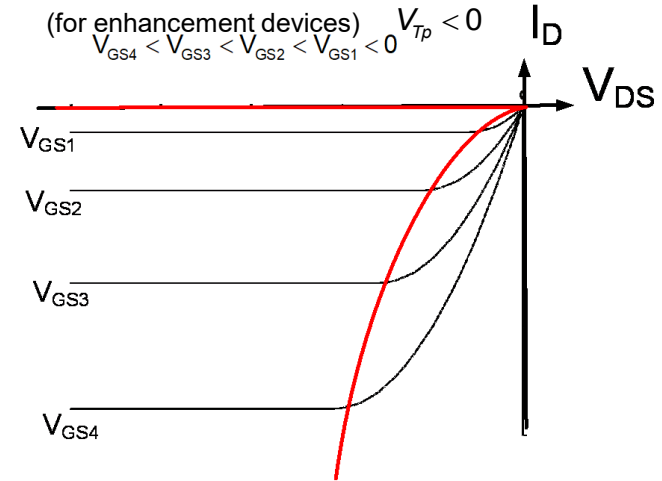
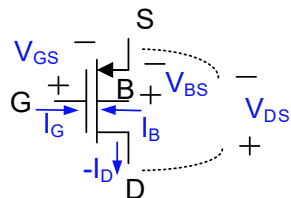
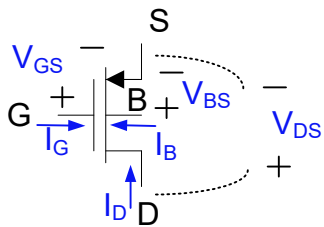
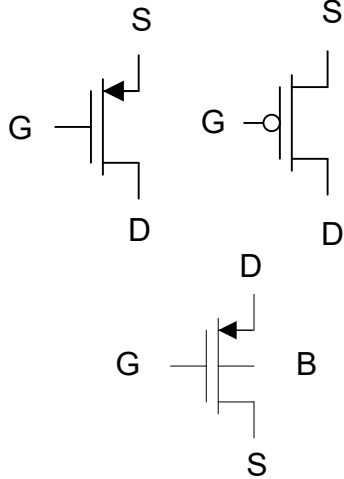
Negative V_{DS} and V_{GS} cause a negative I_D

Functional form of models are the same, just sign differences and some parameter differences (usually mobility is the most important)

n-channel p-channel modeling



p-channel MOSFET

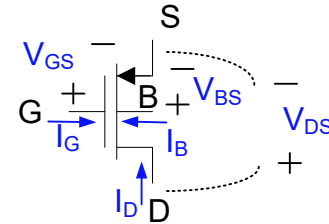
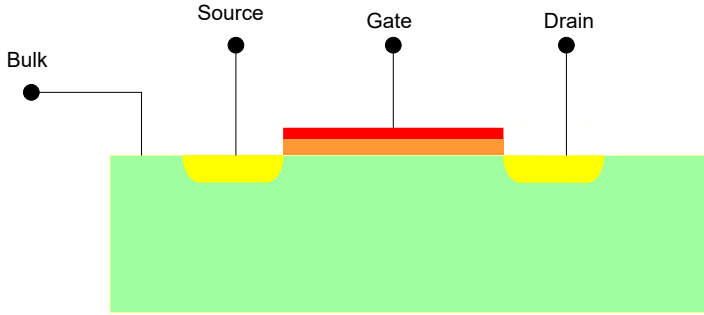


$$I_D = \begin{cases} 0 & V_{GS} \geq V_{Tp} \\ -\mu_p C_{OX} \frac{W}{L} \left(V_{GS} - V_{Tp} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \leq V_{Tp} \quad V_{DS} > V_{GS} - V_{Tp} \\ -\mu_p C_{OX} \frac{W}{2L} (V_{GS} - V_{Tp})^2 & V_{GS} \leq V_{Tp} \quad V_{DS} \leq V_{GS} - V_{Tp} \end{cases}$$

$$I_G = I_B = 0$$

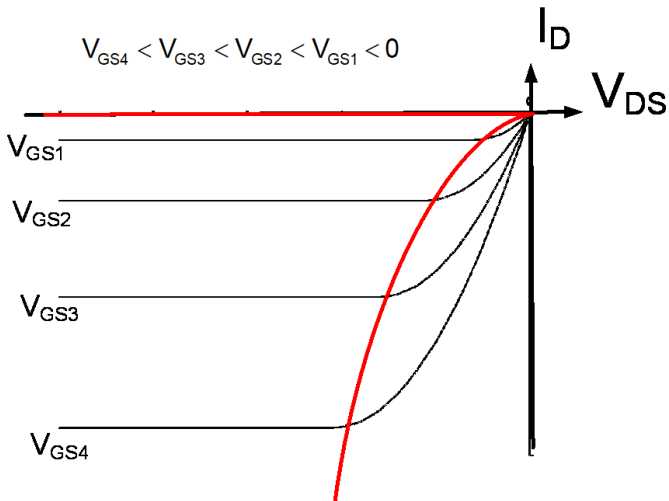
- Actually should use C_{OXp} and C_{OXn} but they are usually almost identical in most processes
- $\mu_n \approx 3\mu_p$
- May choose to model $-I_D$ which will be non-negative

n-channel p-channel modeling



(for enhancement devices)

$$V_{GS4} < V_{GS3} < V_{GS2} < V_{GS1} < 0$$



$$I_D = \begin{cases} 0 & V_{GS} \geq V_{Tp} \\ -\mu_p C_{ox} \frac{W}{L} \left(V_{GS} - V_{Tp} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \leq V_{Tp} \quad V_{DS} > V_{GS} - V_{Tp} \\ -\mu_p C_{ox} \frac{W}{2L} (V_{GS} - V_{Tp})^2 & V_{GS} \leq V_{Tp} \quad V_{DS} \leq V_{GS} - V_{Tp} \end{cases}$$

$I_G = I_B = 0$

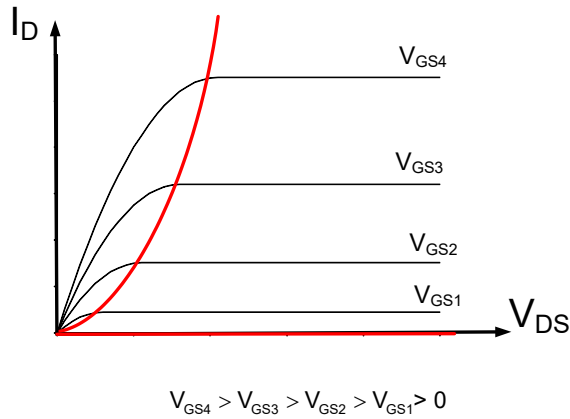
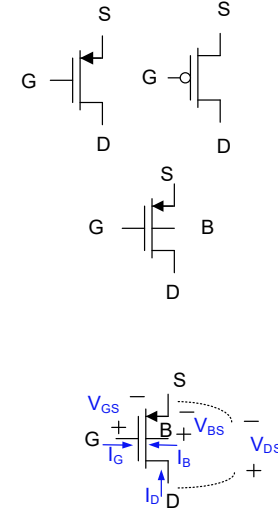
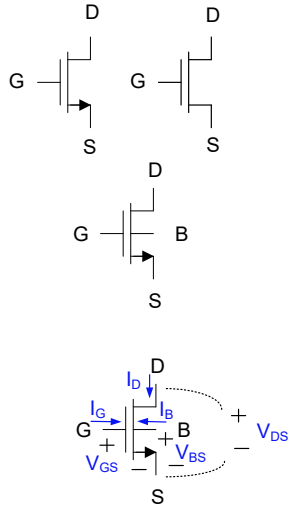
Alternate equivalent representation w/o sign convention

$$|I_D| = \begin{cases} 0 & |V_{GS}| \leq |V_{Tp}| \\ \mu_p C_{ox} \frac{W}{L} \left(|V_{GS}| - |V_{Tp}| - \frac{|V_{DS}|}{2} \right) |V_{DS}| & |V_{GS}| \geq |V_{Tp}| \quad |V_{DS}| < |V_{GS}| - |V_{Tp}| \\ \mu_p C_{ox} \frac{W}{2L} (|V_{GS}| - |V_{Tp}|)^2 & |V_{GS}| \geq |V_{Tp}| \quad |V_{DS}| \geq |V_{GS}| - |V_{Tp}| \end{cases}$$

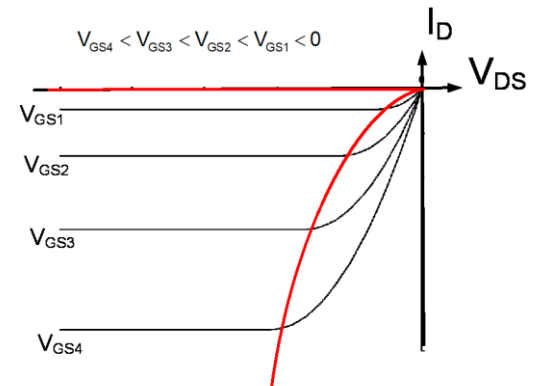
$I_G = I_B = 0$

These look like those for the n-channel device but with | |

n-channel p-channel modeling



Models essentially the same with different signs and model parameters



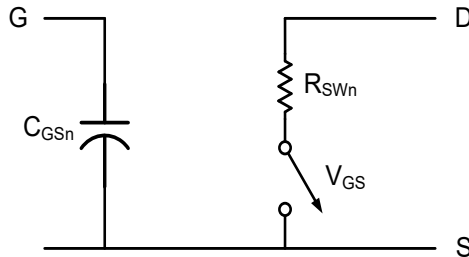
$$I_D = \begin{cases} 0 & V_{GS} \leq V_{Tn} \\ \mu_n C_{ox} \frac{W}{L} \left(V_{GS} - V_{Tn} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \geq V_{Tn}, V_{DS} < V_{GS} - V_{Tn} \\ \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_{Tn})^2 & V_{GS} \geq V_{Tn}, V_{DS} \geq V_{GS} - V_{Tn} \end{cases}$$

$I_G = I_B = 0$

$$I_D = \begin{cases} 0 & V_{GS} \geq V_{Tp} \\ -\mu_p C_{ox} \frac{W}{L} \left(V_{GS} - V_{Tp} - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \leq V_{Tp}, V_{DS} > V_{GS} - V_{Tp} \\ -\mu_p C_{ox} \frac{W}{2L} (V_{GS} - V_{Tp})^2 & V_{GS} \leq V_{Tp}, V_{DS} \leq V_{GS} - V_{Tp} \end{cases}$$

$I_G = I_B = 0$

Model Relationships



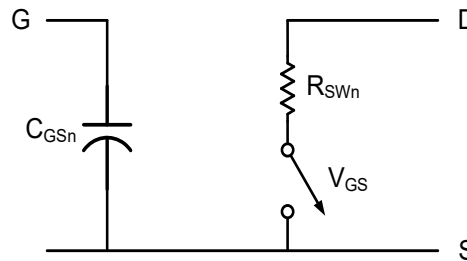
Determine R_{SW} and C_{GS} in the switch-level model for an **n-channel** MOSFET from square-law model in the 0.5u ON CMOS process if $L=1\mu$, $W=1\mu$

(Assume $\mu_n C_{OX}=100\mu AV^{-2}$, $C_{OX}=2.5fFu^{-2}$, $V_{T0}=1V$, $V_{DD}=3.5V$, $V_{SS}=0$)

$$I_D = \begin{cases} 0 & V_{GS} \leq V_T \\ \mu C_{OX} \frac{W}{L} \left(V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \geq V_T \quad V_{DS} < V_{GS} - V_T \\ \mu C_{OX} \frac{W}{2L} (V_{GS} - V_T)^2 & V_{GS} \geq V_T \quad V_{DS} \geq V_{GS} - V_T \end{cases}$$

when SW is on, operation is “deep” triode

Model Relationships



Determine R_{SW} and C_{GS} for an **n-channel** MOSFET from square-law model in the 0.5u ON CMOS process if $L=1\mu$, $W=1\mu$

(Assume $\mu_n C_{OX}=100\mu AV^{-2}$, $C_{OX}=2.5fFu^{-2}$, $V_{T0}=1V$, $V_{DD}=3.5V$, $V_{SS}=0$)

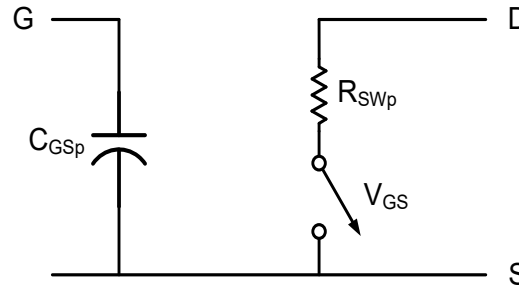
When on operating in deep triode

$$I_D = \mu C_{OX} \frac{W}{L} \left(V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS} \cong \mu C_{OX} \frac{W}{L} (V_{GS} - V_T) V_{DS}$$

$$R_{SQ} = \frac{V_{DS}}{I_D} \Bigg|_{V_{GS}=V_{DD}} = \frac{1}{\mu C_{OX} \frac{W}{L} (V_{GS} - V_T)} \Bigg|_{V_{GS}=3.5V} = \frac{1}{(10^{-4}) \left(\frac{1}{1} \right) (3.5 - 1)} = 4K\Omega$$

$$C_{GS} = C_{OX} WL = (2.5fF\mu^{-2})(1\mu^2) = 2.5fF$$

Model Relationships



Determine R_{SW} and C_{GS} for an **p-channel** MOSFET from square-law model in the 0.5u ON CMOS process if $L=1\mu$, $W=1\mu$

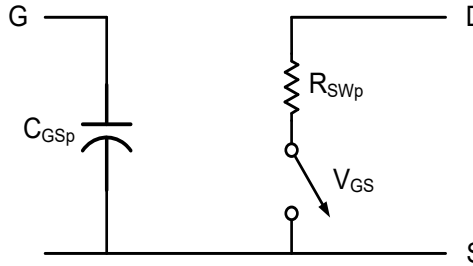
($\mu_p C_{OX}=33\mu AV^{-2}$, $\mu_n C_{OX}=100\mu AV^{-2}$, $C_{OX}=2.5fFu^{-2}$, $V_{T0}=1V$, $V_{DD}=3.5V$, $V_{SS}=0$)

Observe $\mu_n \setminus \mu_p \approx 3$

$$-I_D = \begin{cases} 0 & V_{GS} \geq V_T \\ \mu C_{OX} \frac{W}{L} \left(V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \leq V_T \quad V_{DS} > V_{GS} - V_T \\ \mu C_{OX} \frac{W}{2L} (V_{GS} - V_T)^2 & V_{GS} \leq V_T \quad V_{DS} \leq V_{GS} - V_T \end{cases}$$

When SW is on, operation is “deep” triode

Model Relationships



Determine R_{SW} and C_{GS} for an p-channel MOSFET from square-law model in the 0.5u ON CMOS process if $L=1\mu$, $W=1\mu$

($\mu_p C_{OX} = \frac{1}{3} \mu_n C_{OX}$, $\mu_n C_{OX} = 100 \mu A V^{-2}$, $C_{OX} = 2.5 fF \mu^{-2}$, $V_{T0} = 1V$, $V_{DD} = 3.5V$, $V_{SS} = 0$)

$$-I_D = \mu_p C_{OX} \frac{W}{L} \left(V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS} \cong \mu_p C_{OX} \frac{W}{L} (V_{GS} - V_T) V_{DS}$$

$$R_{SQ} = \left. \frac{-V_{DS}}{-I_D} \right|_{V_{GS}=V_{DD}} = \frac{1}{\mu_p C_{OX} \frac{W}{L} (V_{GS} - V_T)} \bigg|_{V_{GS}=3.5V} = \frac{1}{\left(\left(\frac{1}{3} \right) 10^{-4} \right) \left(\frac{1}{1} \right) |3.5 - 1|} = 12 K\Omega$$

$$C_{GS} = C_{OX} WL = (2.5 fF \mu^{-2})(1 \mu^2) = 2.5 fF$$

Observe the resistance of the p-channel device is approximately 3 times larger than that of the n-channel device for same bias and dimensions !

This is due to the difference in mobility between n-type and p-type materials

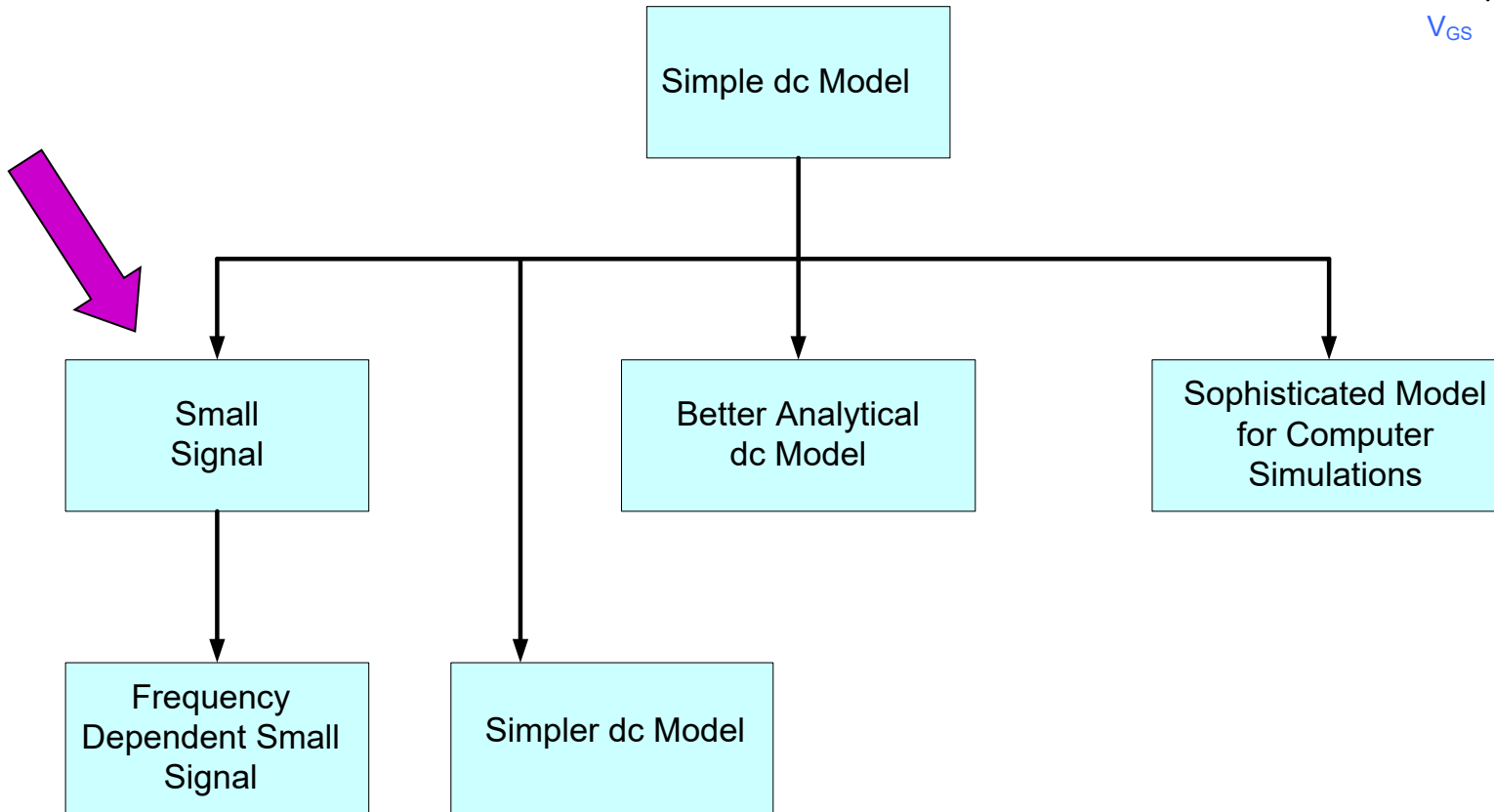
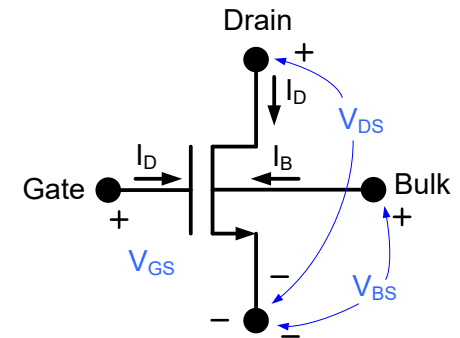
Modeling of the MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.

$$I_D = f_1(V_{GS}, V_{DS}, V_{BS})$$

$$I_G = f_2(V_{GS}, V_{DS}, V_{BS})$$

$$I_B = f_3(V_{GS}, V_{DS}, V_{BS})$$

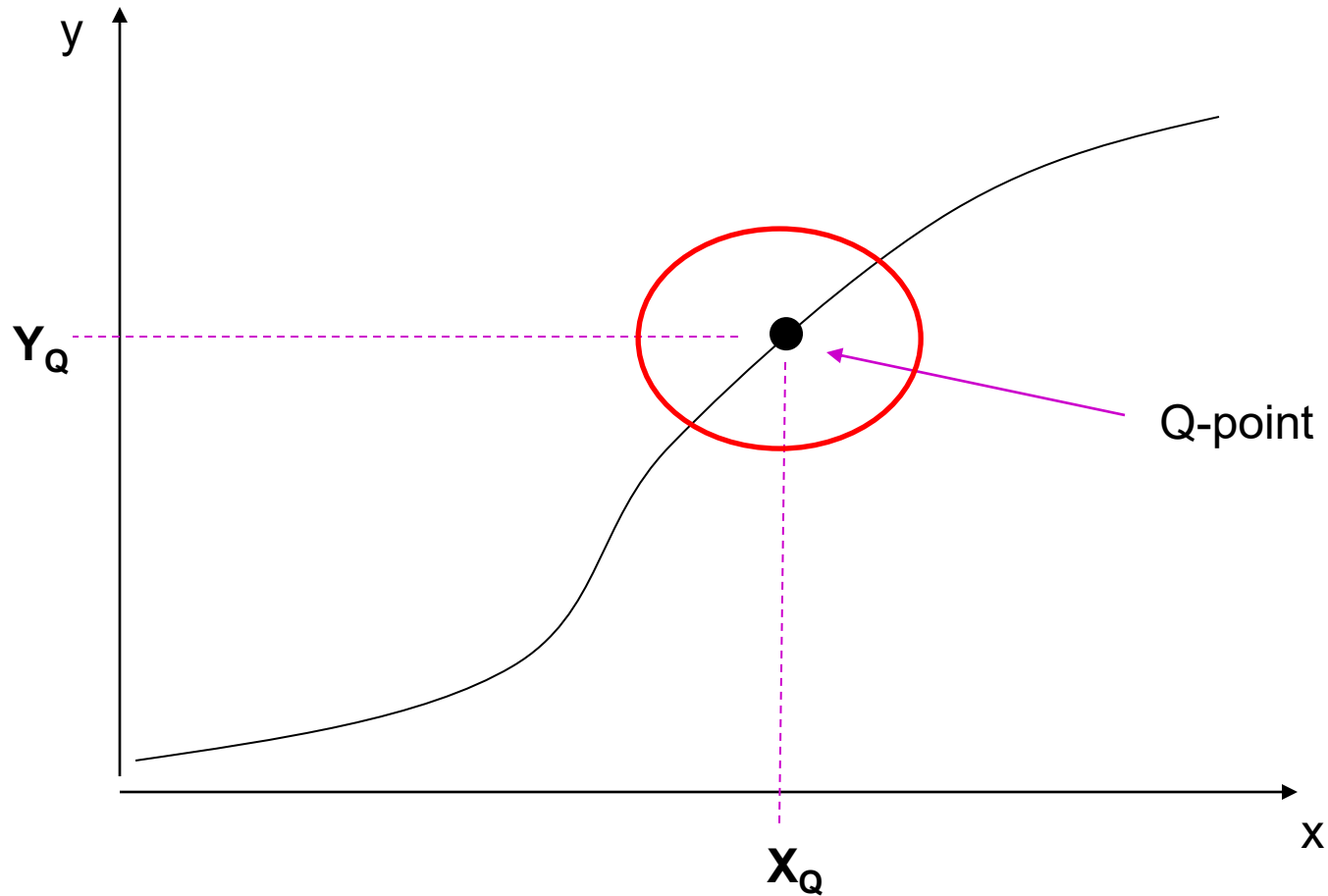


Small-Signal Model

Goal with small signal model is to predict performance of circuit or device in the vicinity of an operating point

Operating point is often termed Q-point

Small-Signal Model



- Behaves linearly in the vicinity of the Q-point
- Analytical expressions for small signal model will be developed later

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET
- BJT



Lets pick up a discussion of another part of the Technology Files before moving to BJT

Technology Files

- Design Rules
- Process Flow (Fabrication Technology)
- Model Parameters

TABLE 2B.1

Process scenario of major process steps in typical n-well CMOS process^a

| | | |
|-----|---|------------|
| 1. | Clean wafer | |
| 2. | GROW THIN OXIDE | |
| 3. | Apply photoresist | |
| 4. | PATTERN n-well | (MASK #1) |
| 5. | Develop photoresist | |
| 6. | Deposit and diffus n-type impurities | |
| 7. | Strip photoresist | |
| 8. | Strip thin oxide | |
| 9. | Grow thin oxide | |
| 10. | Apply layer of Si ₃ N ₄ | |
| 11. | Apply photoresist | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) |
| 13. | Develop photoresist | |
| 14. | Etch Si ₃ N ₄ | |
| 15. | Strip photoresist | |
| | <i>Optional field threshold voltage adjust</i> | |
| | A.1 Apply photoresist | |
| | A.2 PATTERN ANTIMOAT IN SUBSTRATE | (MASK #A1) |
| | A.3 Develop photoresist | |
| | A.4 FIELD IMPLANT (p-type) | |
| | A.5 Strip photoresist | |
| 16. | GROW FIELD OXIDE | |
| 17. | Strip Si ₃ N ₄ | |
| 18. | Strip thin oxide | |
| 19. | GROW GATE OXIDE | |
| 20. | POLYSILICON DEPOSITION (POLY I) | |
| 21. | Apply photoresist | |
| 22. | PATTERN POLYSILICON | (MASK #3) |
| 23. | Develop photoresist | |
| 24. | ETCH POLYSILICON | |

25. Strip photoresist
Optional steps for double polysilicon process
 - B.1 Strip thin oxide
 - B.2 GROW THIN OXIDE
 - B.3 POLYSILICON DEPOSITION (POLY II)
 - B.4 Apply photoresist
 - B.5 PATTERN POLYSILICON (MASK #B1)
 - B.6 Develop photoresist
 - B.7 ETCH POLYSILICON
 - B.8 Strip photoresist
 - B.9 Strip thin oxide

26. Apply photoresist
27. PATTERN P-CHANNEL DRAINS AND SOURCES AND P⁺ GUARD RINGS (p-well ohmic contacts) (MASK #4)
28. Develop photoresist
29. p⁺ IMPLANT
30. Strip photoresist
31. Apply photoresist
32. PATTERN N-CHANNEL DRAINS AND SOURCES AND N⁺ GUARD RINGS (top ohmic contact to substrate) (MASK #5)
33. Develop photoresist
34. n⁺ IMPLANT
35. Strip photoresist
36. Strip thin oxide
37. Grow oxide
38. Apply photoresist
39. PATTERN CONTACT OPENINGS (MASK #6)
40. Develop photoresist
41. Etch oxide
42. Strip photoresist

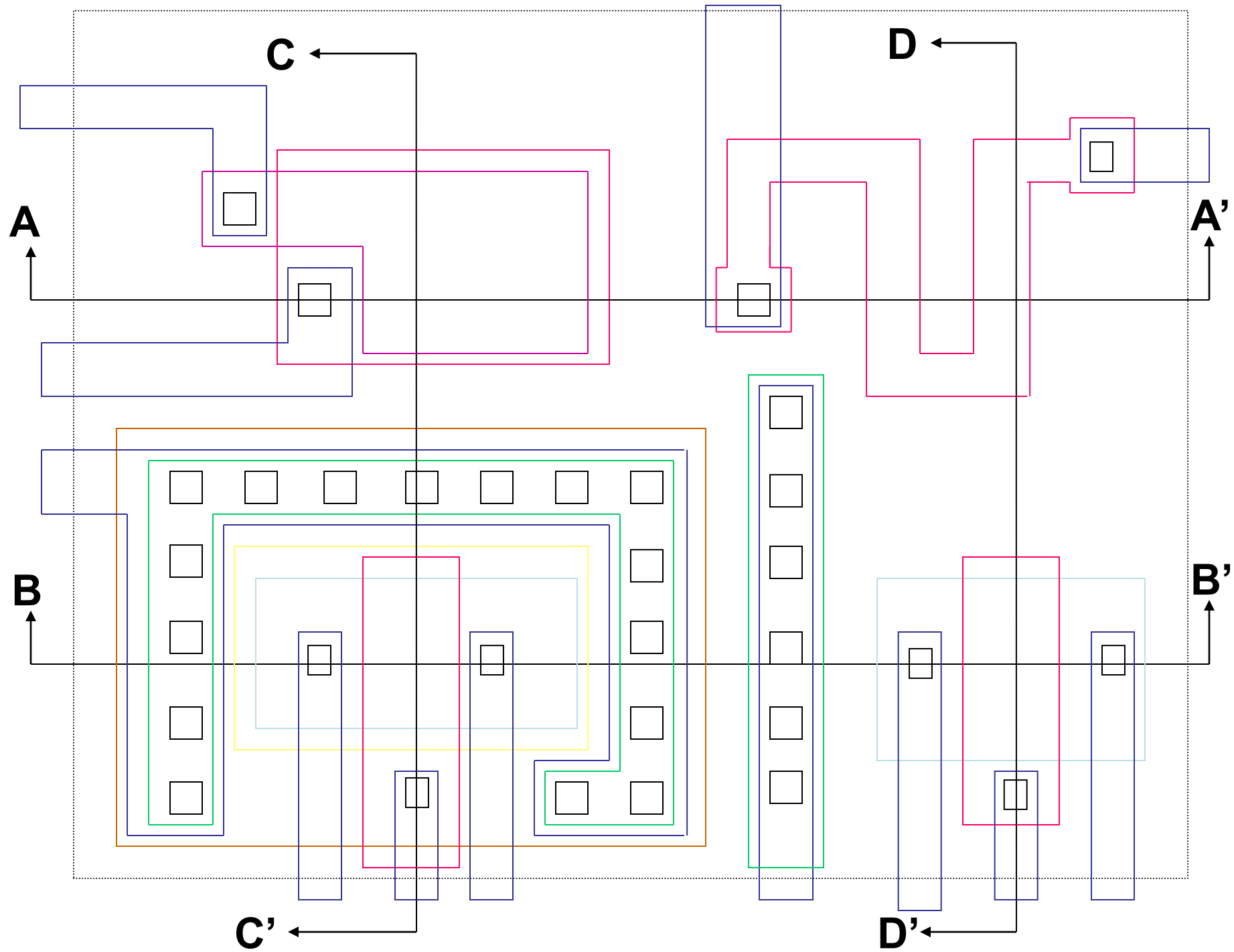
43. APPLY METAL
44. Apply photoresist
45. PATTERN METAL (MASK #7)
46. Develop photoresist
47. Etch metal
48. Strip photoresist
Optional steps for double metal process
 - C.1 Strip thin oxide
 - C.2 DEPOSIT INTERMETAL OXIDE
 - C.3 Apply photoresist
 - C.4 PATTERN VIAS (MASK #C1)
 - C.5 Develop photoresist
 - C.6 Etch oxide
 - C.7 Strip photoresist
 - C.8 APPLY METAL (Metal 2)
 - C.9 Apply photoresist
 - C.10 PATTERN METAL (MASK #C2)
 - C.11 Develop photoresist
 - C.12 Etch metal
 - C.13 Strip photoresist
49. APPLY PASSIVATION
50. Apply photoresist
51. PATTERN PAD OPENINGS (MASK #8)
52. Develop photoresist
53. Etch passivation
54. Strip photoresist
55. ASSEMBLE, PACKAGE AND TEST

Bulk CMOS Process Description

- n-well process
 - Single Metal Only Depicted
 - Double Poly
- This type of process dominates what is used for high-volume “low-cost” processing of integrated circuits today
 - Many process variants and specialized processes are used for lower-volume or niche applications
 - Emphasis in this course will be on the electronics associated with the design of integrated electronic circuits in processes targeting high-volume low-cost products where competition based upon price differentiation may be acute
 - Basic electronics concepts, however, are applicable for lower-volume or niche applications

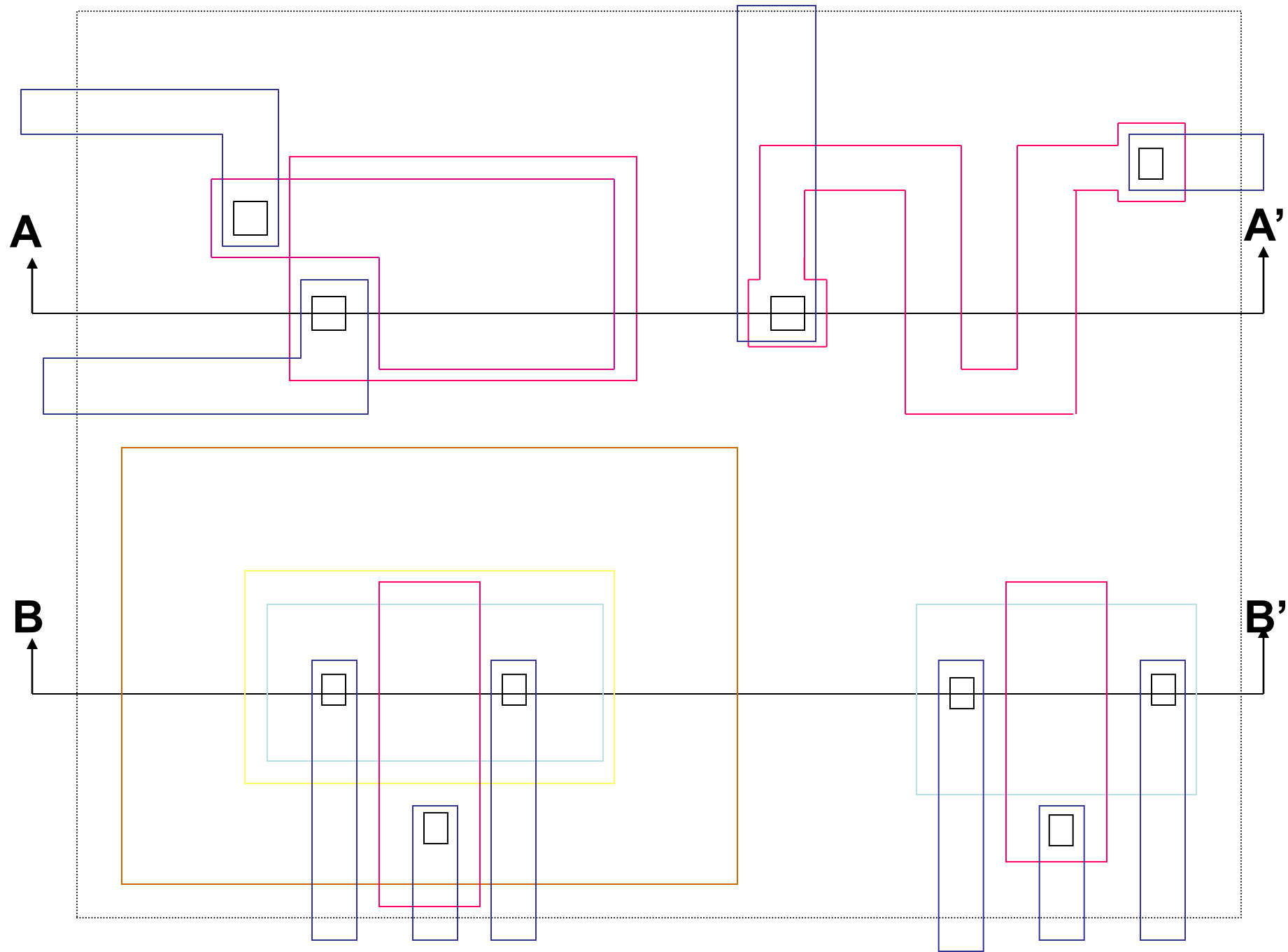
Components Shown

- n-channel MOSFET
- p-channel MOSFET
- Poly Resistor
- Doubly Poly Capacitor

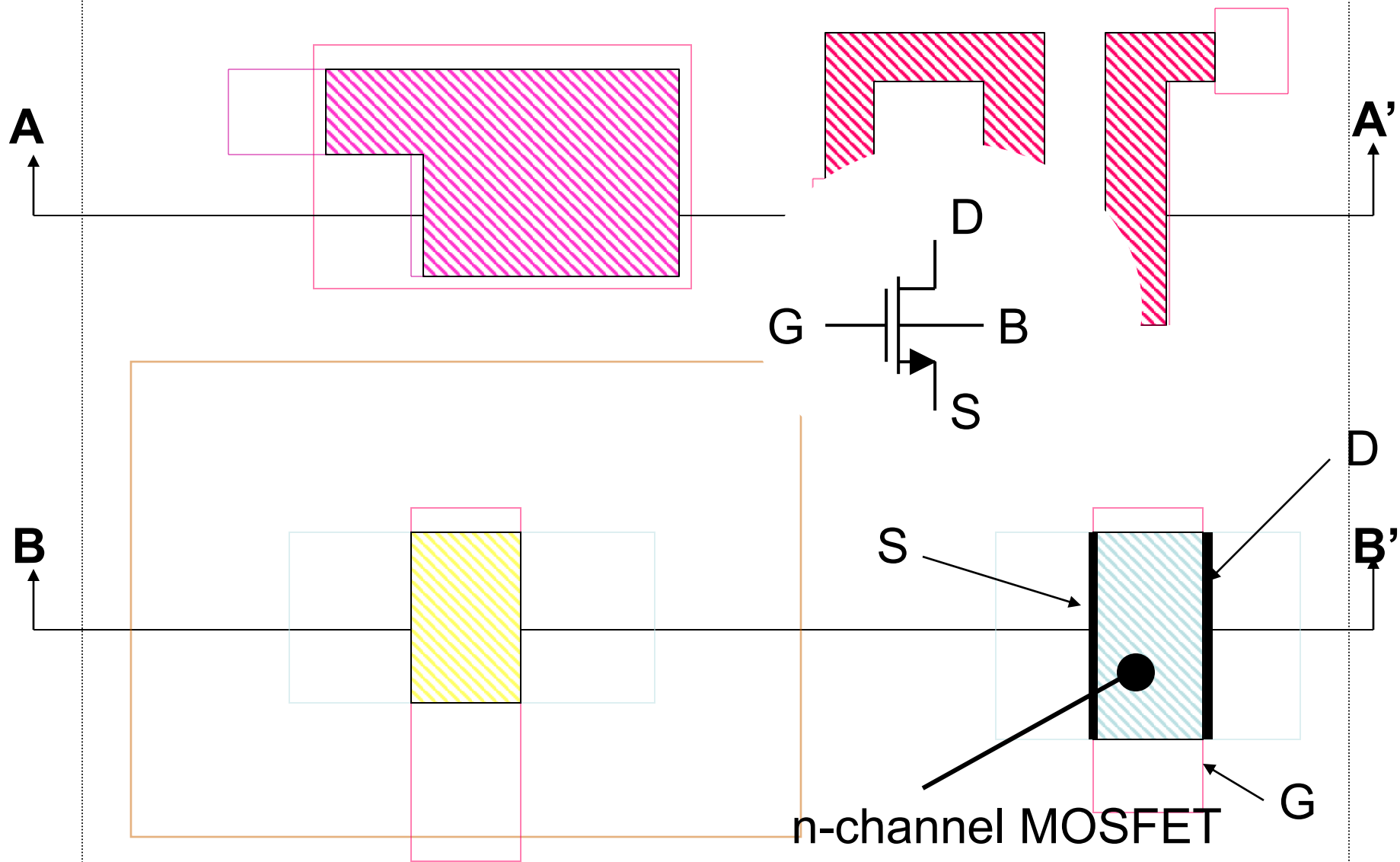


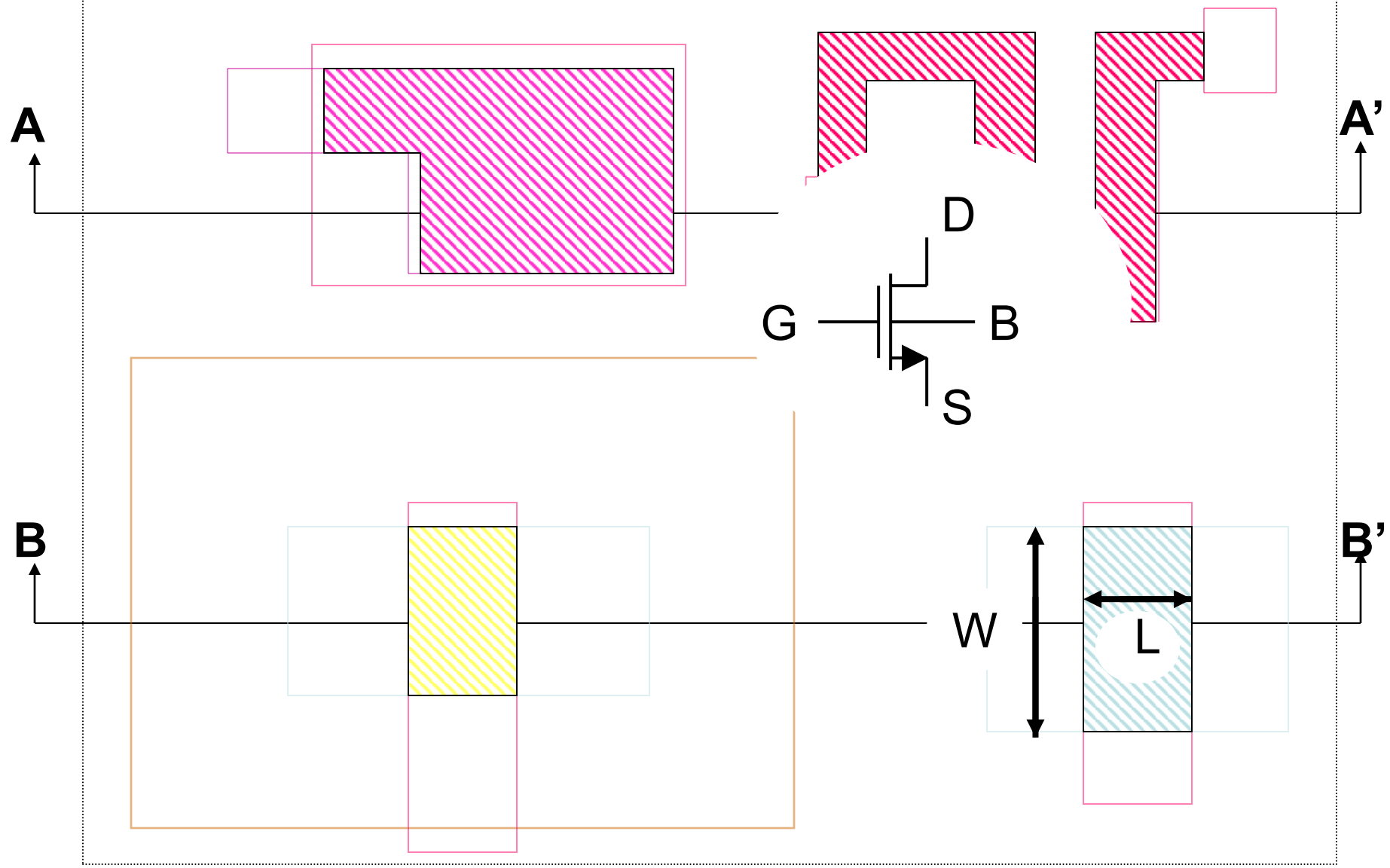
Consider Basic Components Only

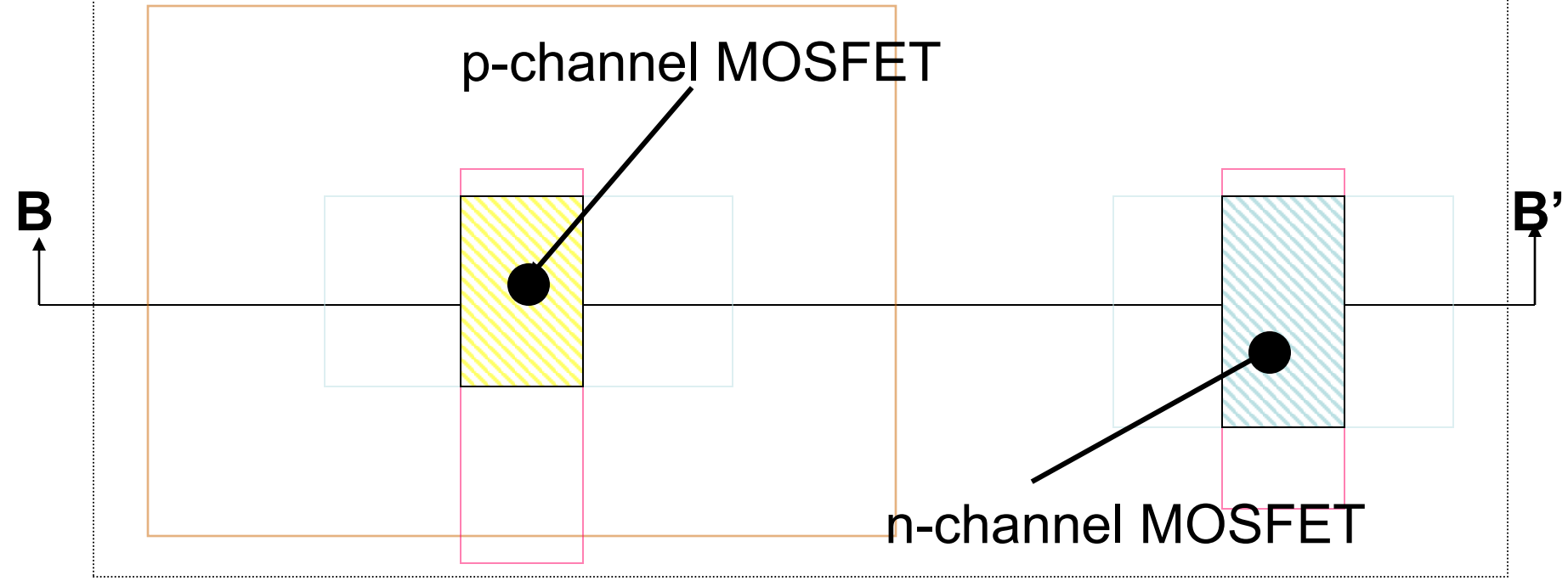
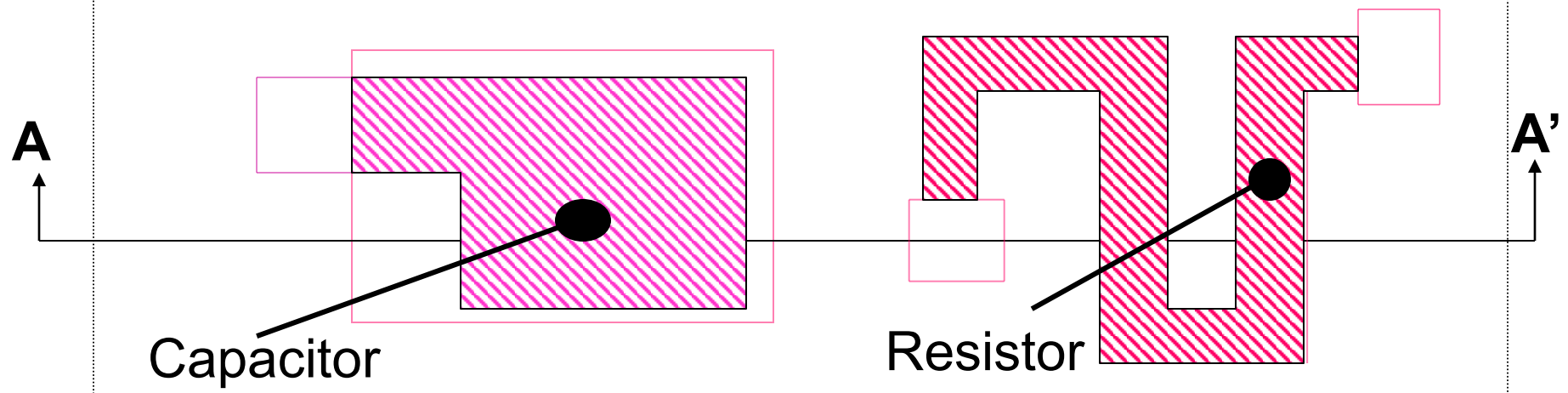
Well Contacts and Guard Rings Will be
Discussed Later



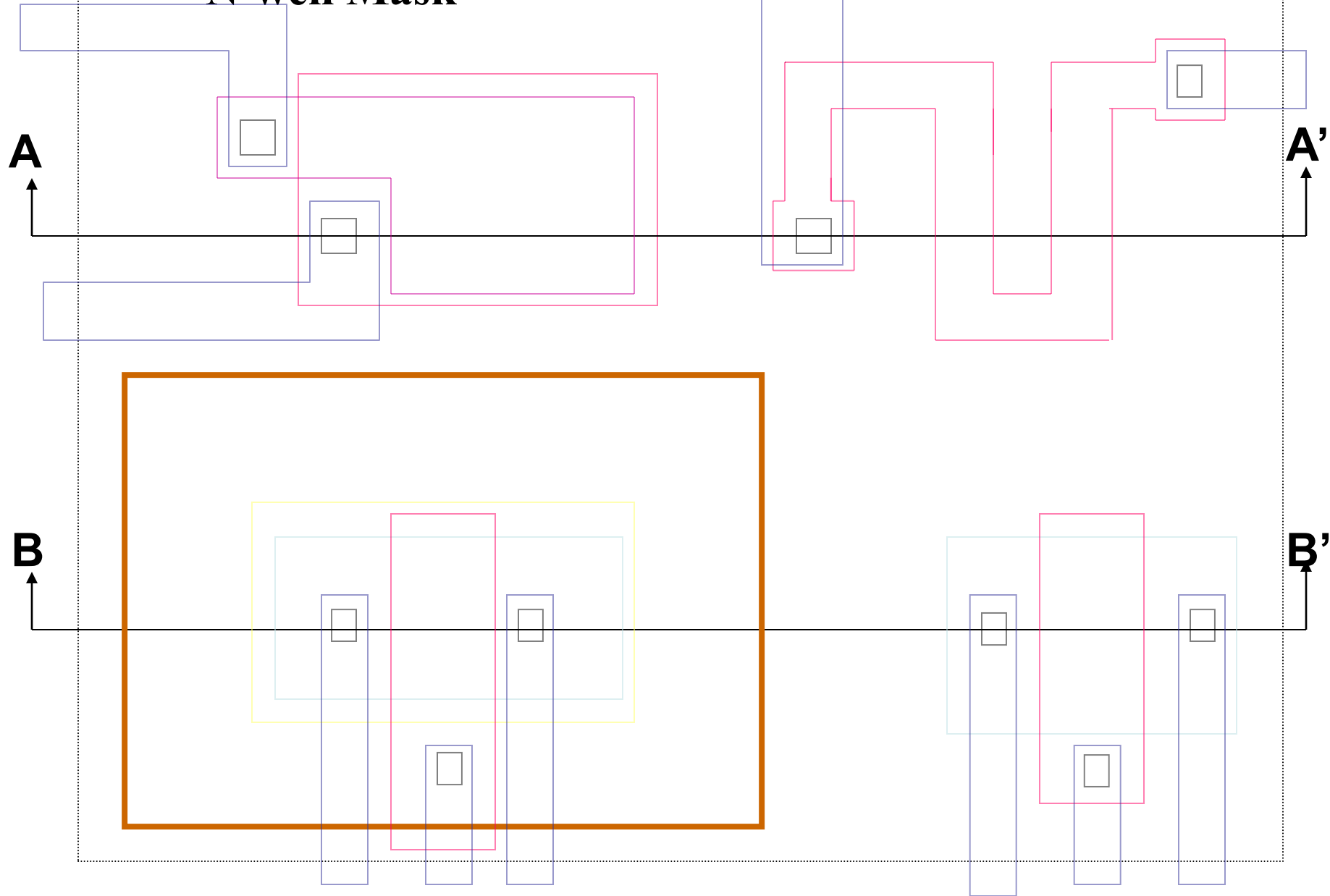
Metal details hidden to reduce clutter







N-well Mask



N-well Mask

A

A'



B

B'



Detailed Description of First Photolithographic Steps Only

- Top View
- Cross-Section View

A



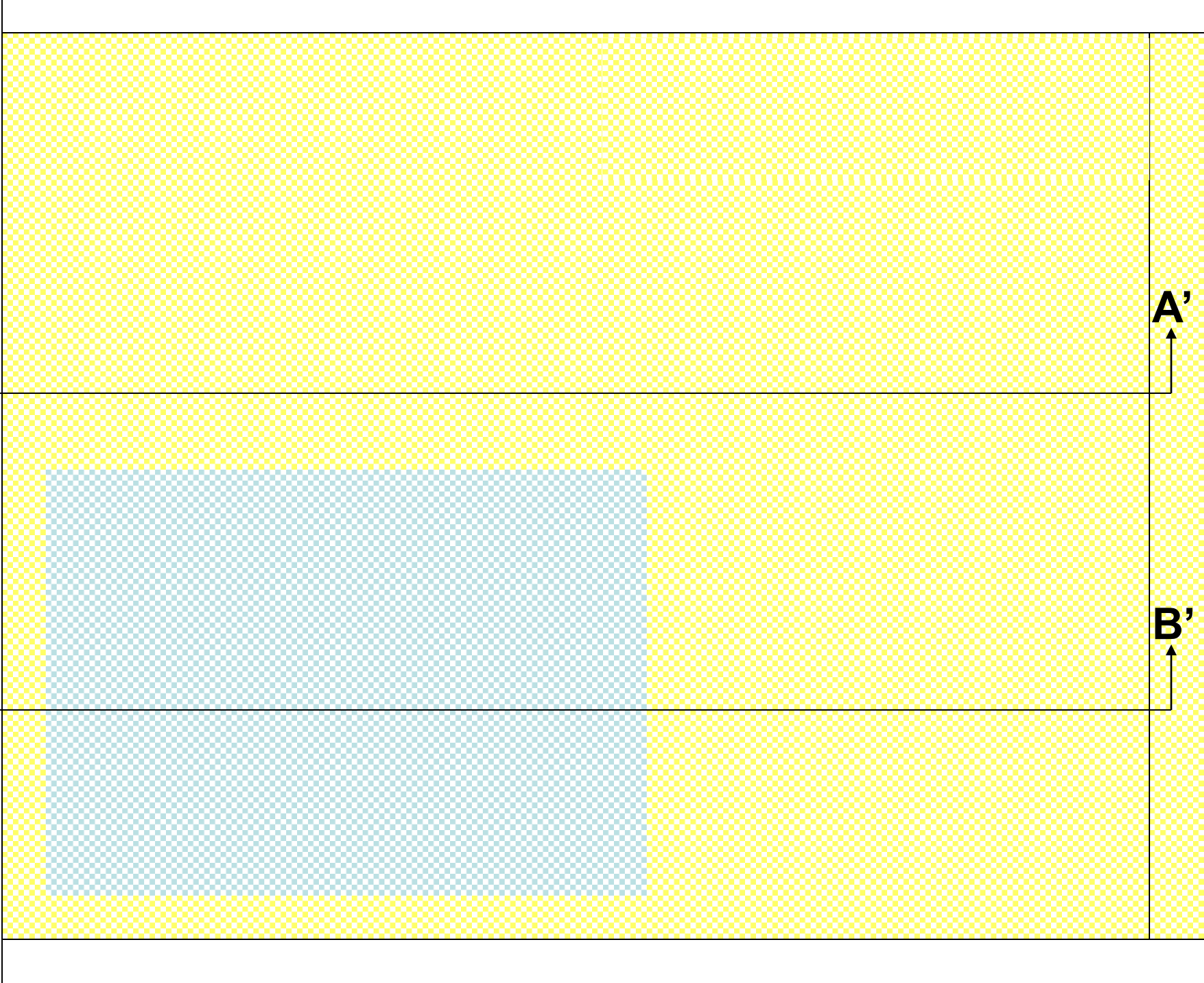
A'



B



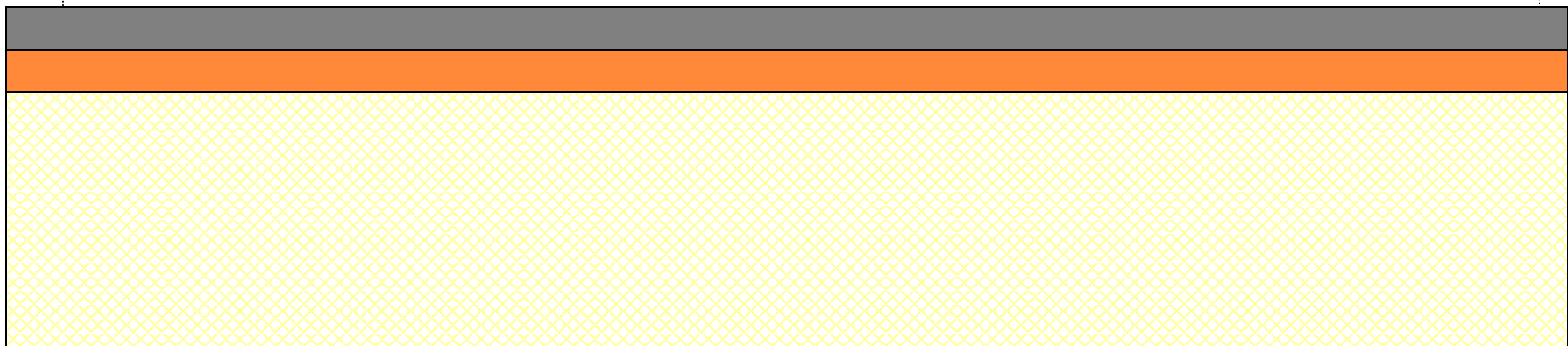
B'



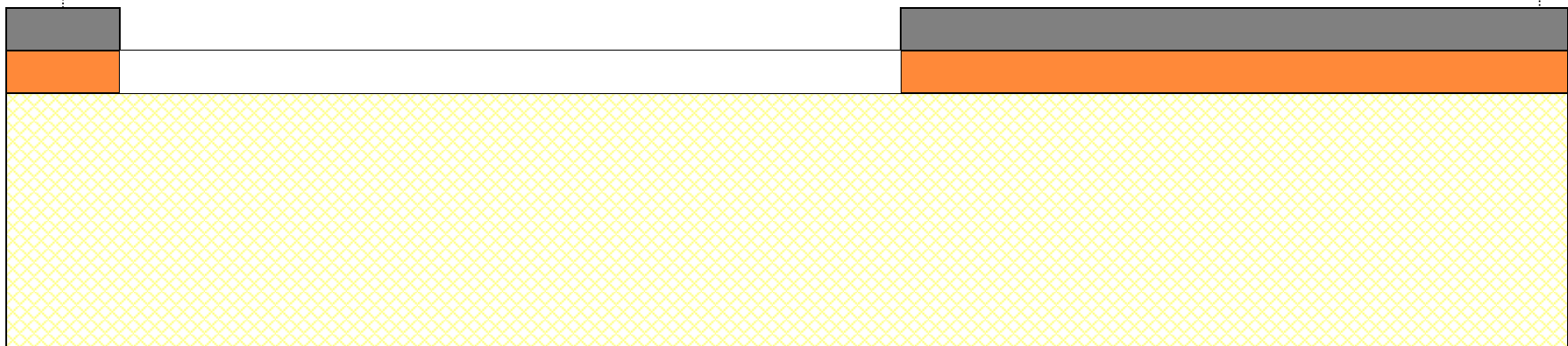
Develop



Shown as mask but actually projection through reticle

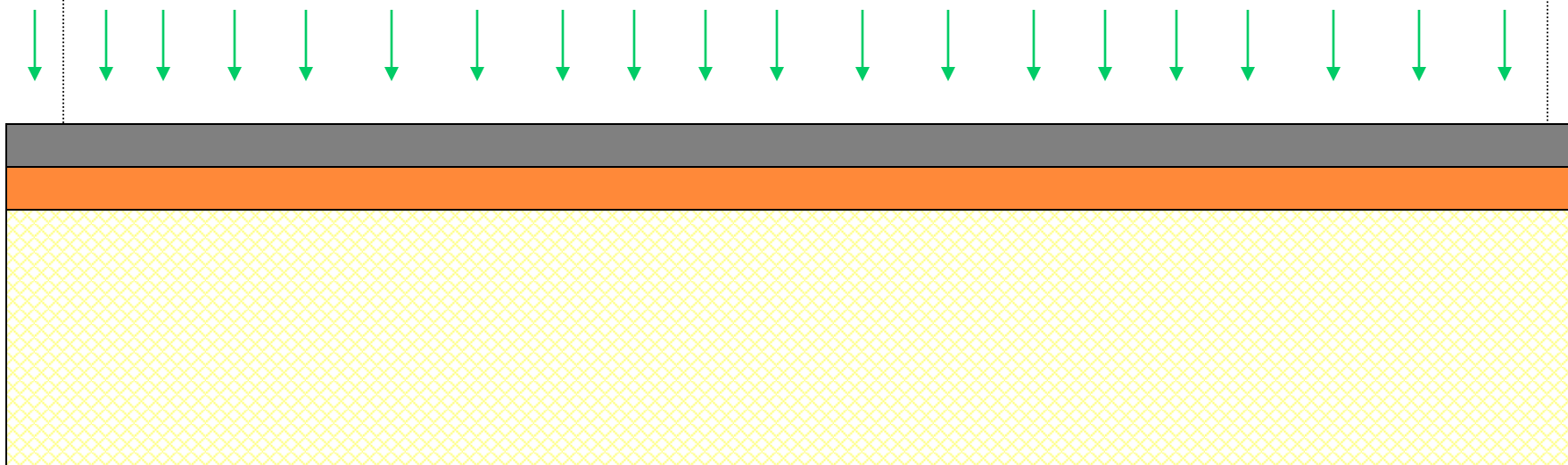


A-A' Section

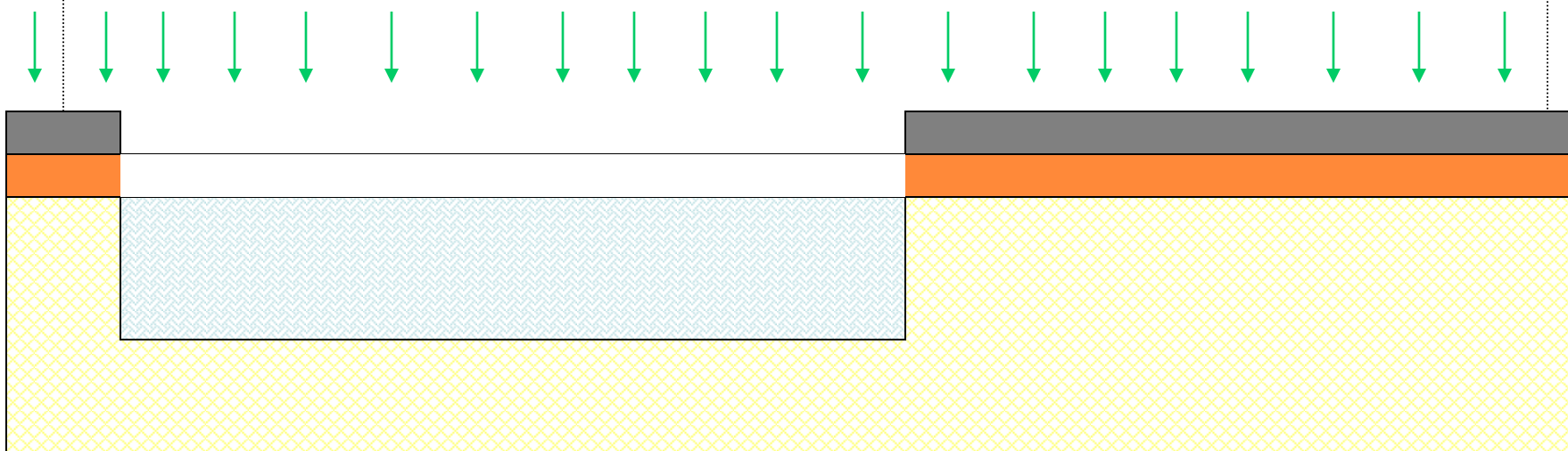


B-B' Section

Implant

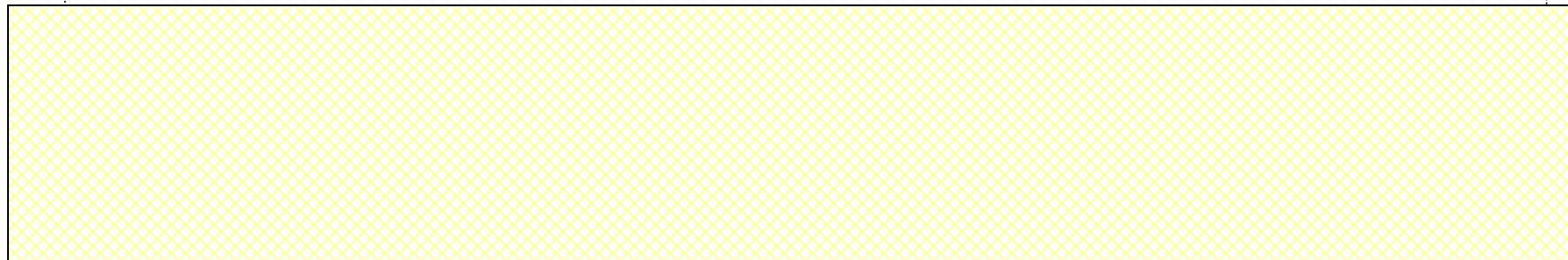


A-A' Section

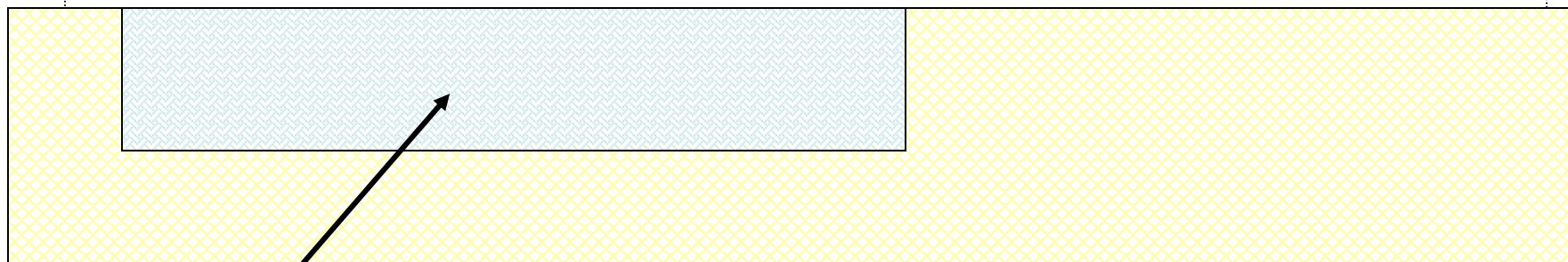


B-B' Section

N-well Mask



A-A' Section



n-well

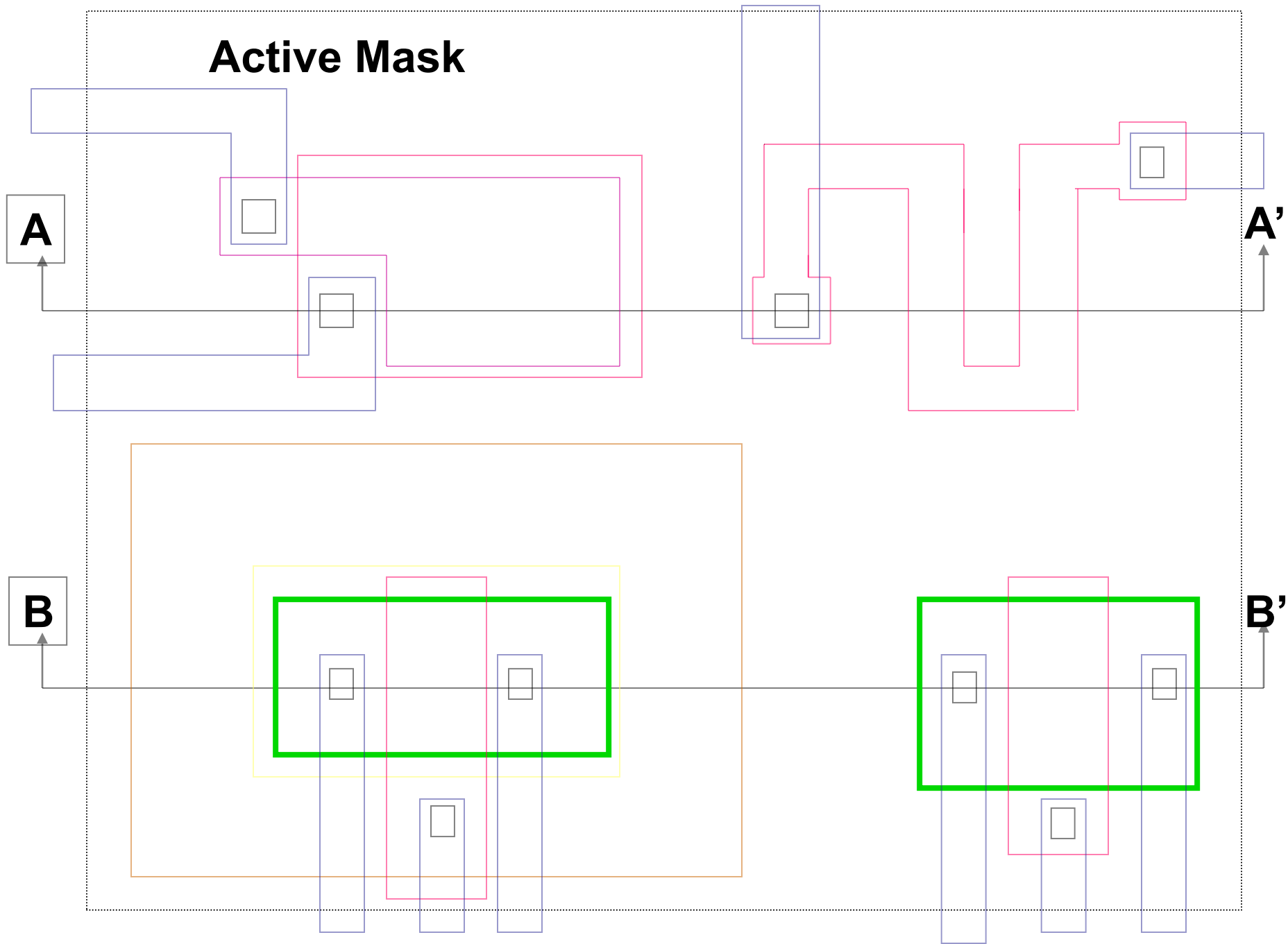
B-B' Section

TABLE 2B.1
Process scenario of major process steps in typical n-well CMOS process^a

| | | | |
|-----|---|------------|-------------|
| 1. | Clean wafer | | |
| 2. | GROW THIN OXIDE | | |
| 3. | Apply photoresist | | |
| 4. | PATTERN n-well | (MASK #1) | n-well mask |
| 5. | Develop photoresist | | |
| 6. | Deposit and diffus n-type impurities | | |
| 7. | Strip photoresist | | |
| 8. | Strip thin oxide | | |
| 9. | Grow thin oxide | | |
| 10. | Apply layer of Si ₃ N ₄ | | |
| 11. | Apply photoresist | | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) | active mask |
| 13. | Develop photoresist | | |
| 14. | Etch Si ₃ N ₄ | | |
| 15. | Strip photoresist | | |
| | <i>Optional field threshold voltage adjust</i> | | |
| | A.1 Apply photoresist | | |
| | A.2 PATTERN ANTIMOAT IN SUBSTRATE | (MASK #A1) | |
| | A.3 Develop photoresist | | |
| | A.4 FIELD IMPLANT p-type) | | |
| | A.5 Strip photoresist | | |
| 16. | GROW FIELD OXIDE | | |
| 17. | Strip Si ₃ N ₄ | | |
| 18. | Strip thin oxide | | |
| 19. | GROW GATE OXIDE | | |
| 20. | POLYSILICON DEPOSITION (POLY I) | | |
| 21. | Apply photoresist | | |
| 22. | PATTERN POLYSILICON | (MASK #3) | |
| 23. | Develop photoresist | | |
| 24. | ETCH POLYSILICON | | |



Active Mask



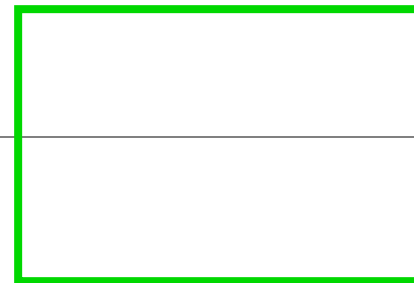
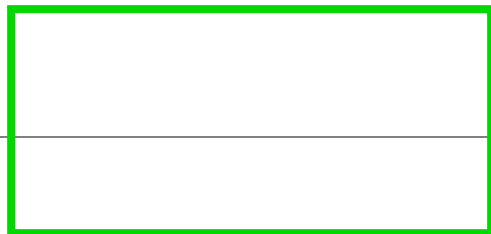
Active Mask

A

A'

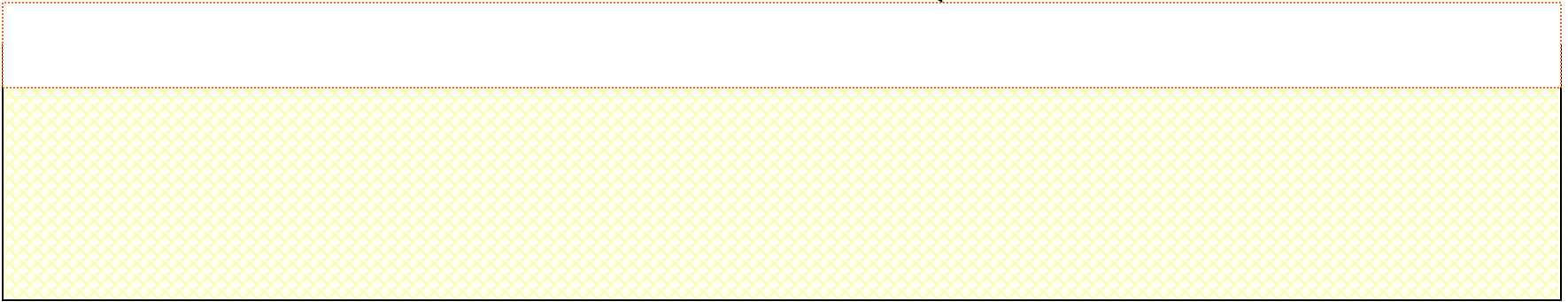
B

B'



Active Mask

Field Oxide



A-A' Section

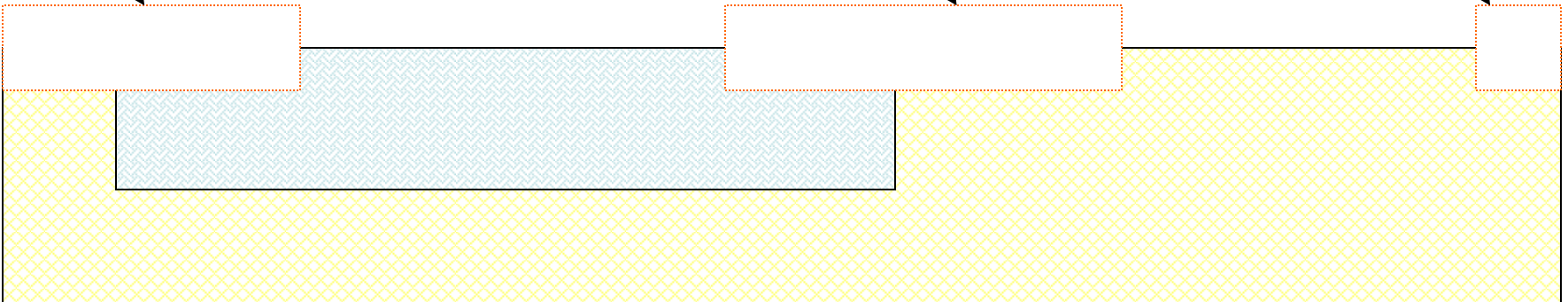
Field Oxide



Field Oxide



Field Oxide



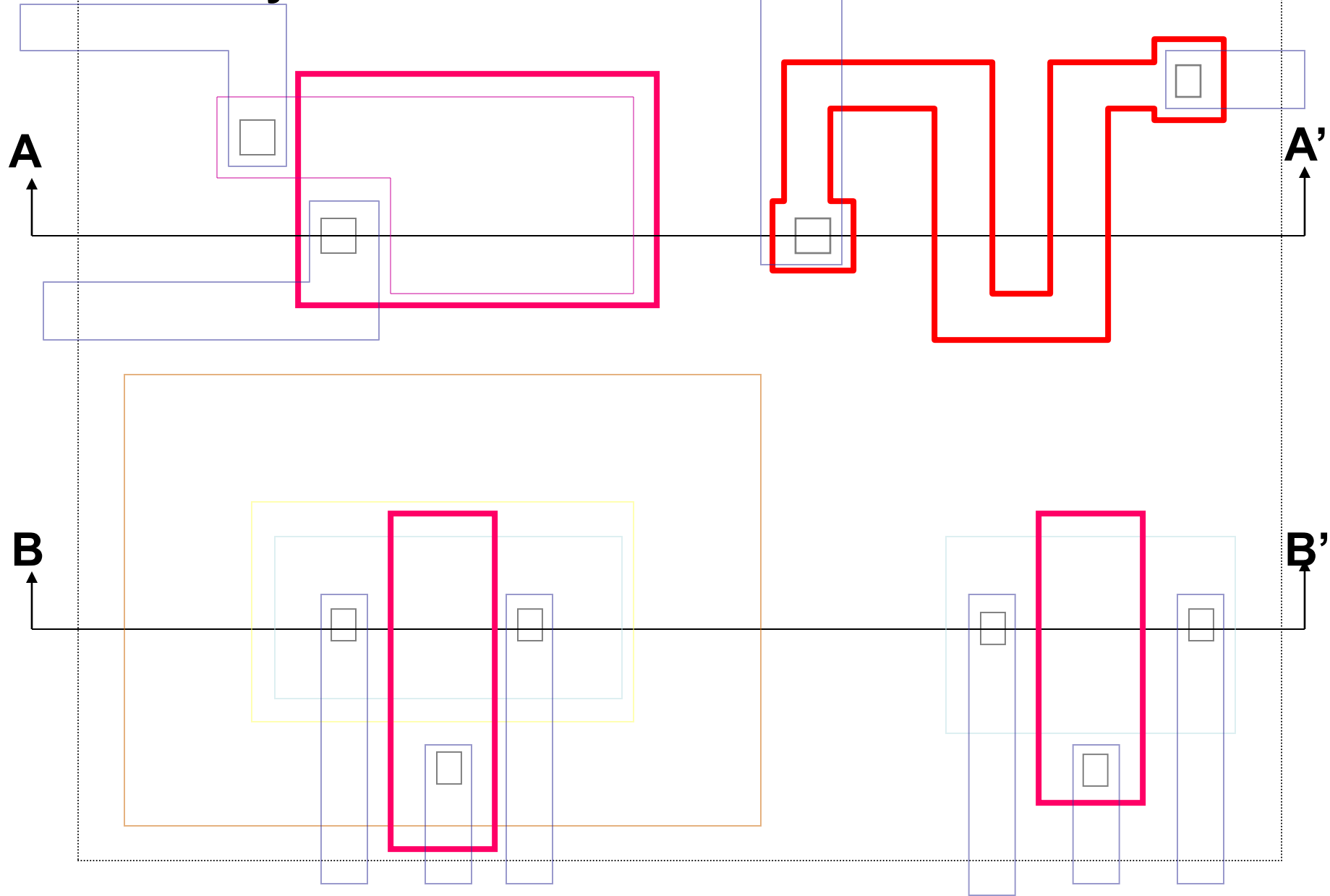
B-B' Section

TABLE 2B.1
Process scenario of major process steps in typical n-well CMOS process^a

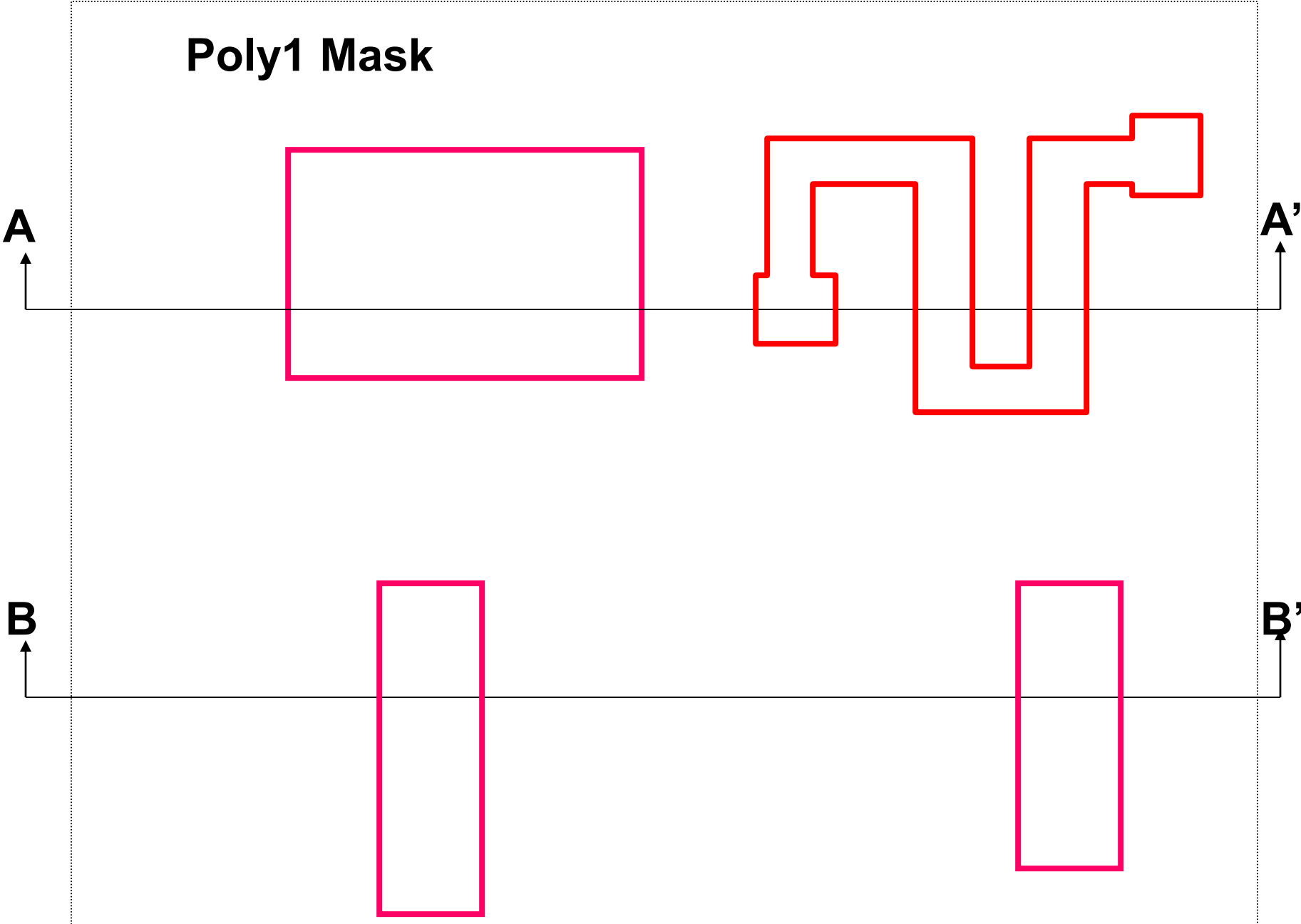
| | | | |
|-----|---|------------|-------------|
| 1. | Clean wafer | | |
| 2. | GROW THIN OXIDE | | |
| 3. | Apply photoresist | | |
| 4. | PATTERN n-well | (MASK #1) | n-well mask |
| 5. | Develop photoresist | | |
| 6. | Deposit and diffus n-type impurities | | |
| 7. | Strip photoresist | | |
| 8. | Strip thin oxide | | |
| 9. | Grow thin oxide | | |
| 10. | Apply layer of Si ₃ N ₄ | | |
| 11. | Apply photoresist | | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) | active mask |
| 13. | Develop photoresist | | |
| 14. | Etch Si ₃ N ₄ | | |
| 15. | Strip photoresist | | |
| | <i>Optional field threshold voltage adjust</i> | | |
| | A.1 Apply photoresist | | |
| | A.2 PATTERN ANTIMOAT IN SUBSTRATE | (MASK #A1) | |
| | A.3 Develop photoresist | | |
| | A.4 FIELD IMPLANT (p-type) | | |
| | A.5 Strip photoresist | | |
| 16. | GROW FIELD OXIDE | | |
| 17. | Strip Si ₃ N ₄ | | |
| 18. | <u>Strip thin oxide</u> | | |
| 19. | <u>GROW GATE OXIDE</u> | | |
| 20. | POLYSILICON DEPOSITION (POLY I) | | |
| 21. | Apply photoresist | | |
| 22. | PATTERN POLYSILICON | (MASK #3) | Poly I mask |
| 23. | Develop photoresist | | |
| 24. | ETCH POLYSILICON | | |



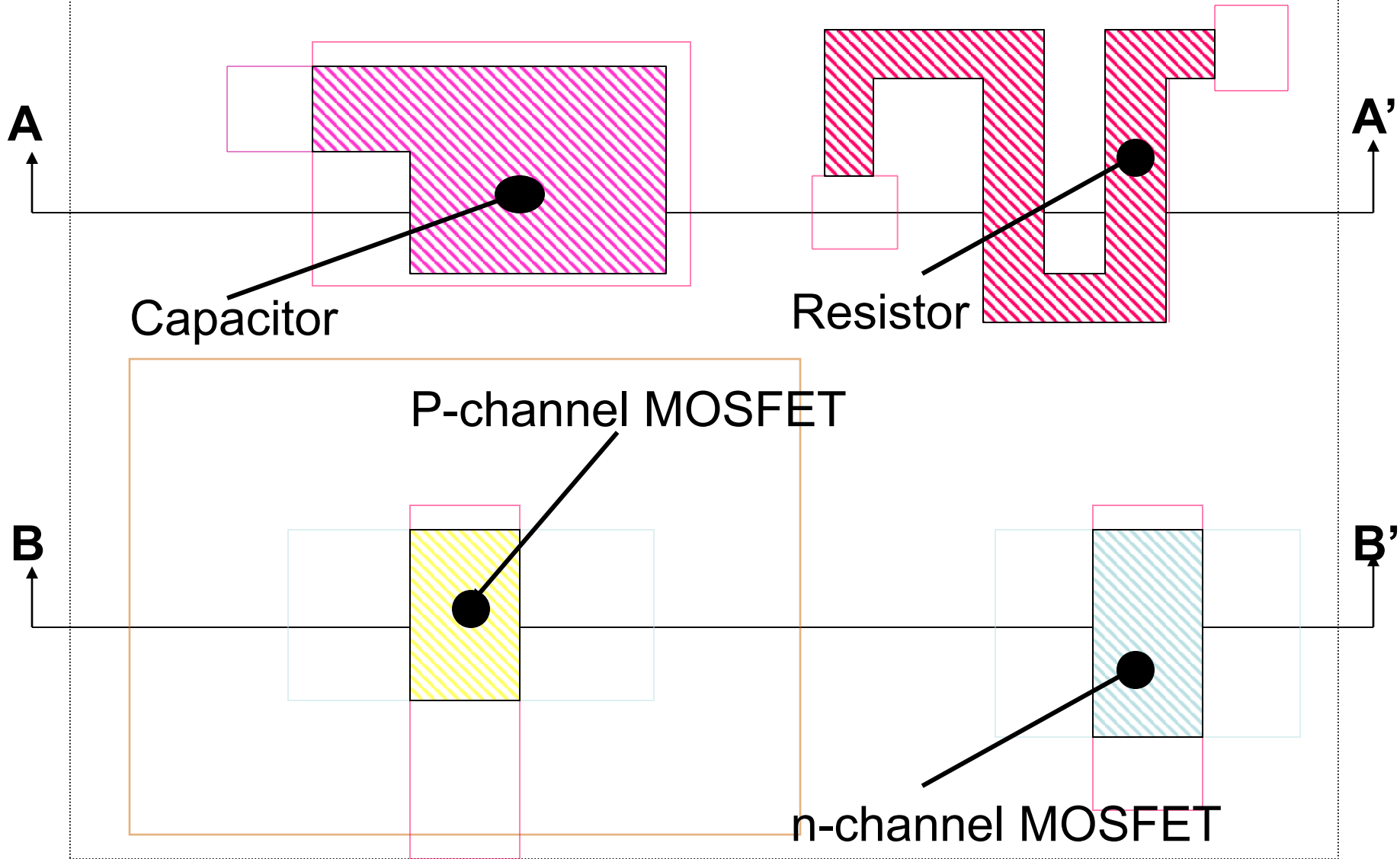
Poly1 Mask



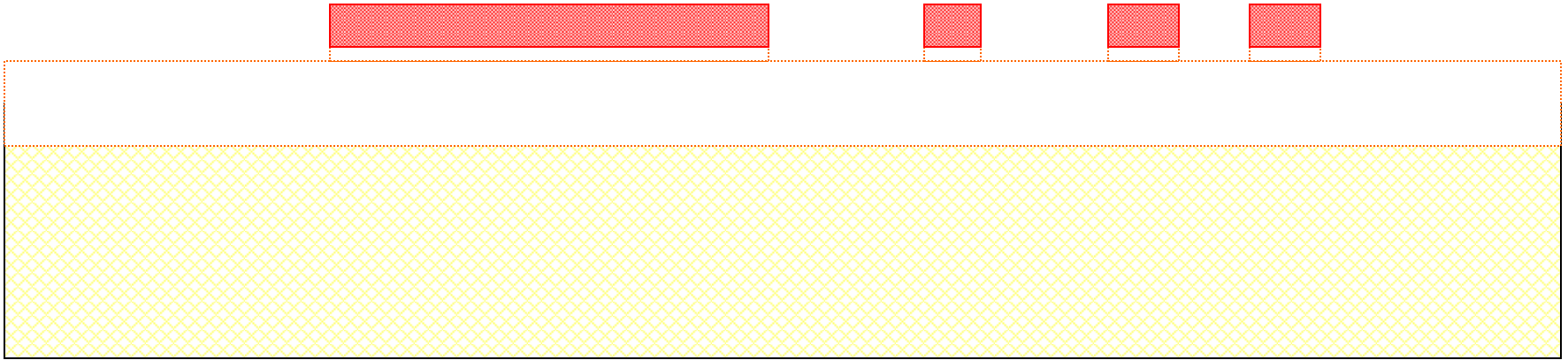
Poly1 Mask



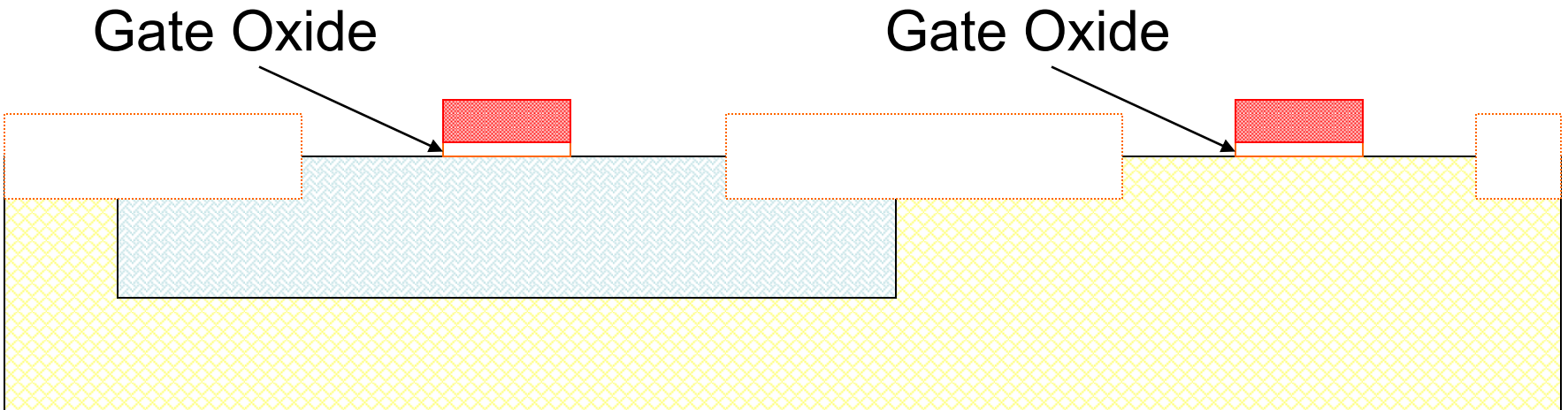
Poly plays a key role in all four types of devices !



Poly 1 Mask



A-A' Section



B-B' Section

TABLE 2B.1

Process scenario of major process steps in typical n-well CMOS process^a

- | | | |
|-----|---|------------|
| 1. | Clean wafer | |
| 2. | GROW THIN OXIDE | |
| 3. | Apply photoresist | |
| 4. | PATTERN n-well | (MASK #1) |
| 5. | Develop photoresist | |
| 6. | Deposit and diffus n-type impurities | |
| 7. | Strip photoresist | |
| 8. | Strip thin oxide | |
| 9. | Grow thin oxide | |
| 10. | Apply layer of Si ₃ N ₄ | |
| 11. | Apply photoresist | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) |
| 13. | Develop photoresist | |
| 14. | Etch Si ₃ N ₄ | |
| 15. | Strip photoresist | |
| | <i>Optional field threshold voltage adjust</i> | |
| | A.1 Apply photoresist | |
| | A.2 PATTERN ANTIMOAT IN SUBSTRATE | (MASK #A1) |
| | A.3 Develop photoresist | |
| | A.4 FIELD IMPLANT (p-type) | |
| | A.5 Strip photoresist | |
| 16. | GROW FIELD OXIDE | |
| 17. | Strip Si ₃ N ₄ | |
| 18. | Strip thin oxide | |
| 19. | GROW GATE OXIDE | |
| 20. | POLYSILICON DEPOSITION (POLY I) | |
| 21. | Apply photoresist | |
| 22. | PATTERN POLYSILICON | (MASK #3) |
| 23. | Develop photoresist | |
| 24. | ETCH POLYSILICON | |

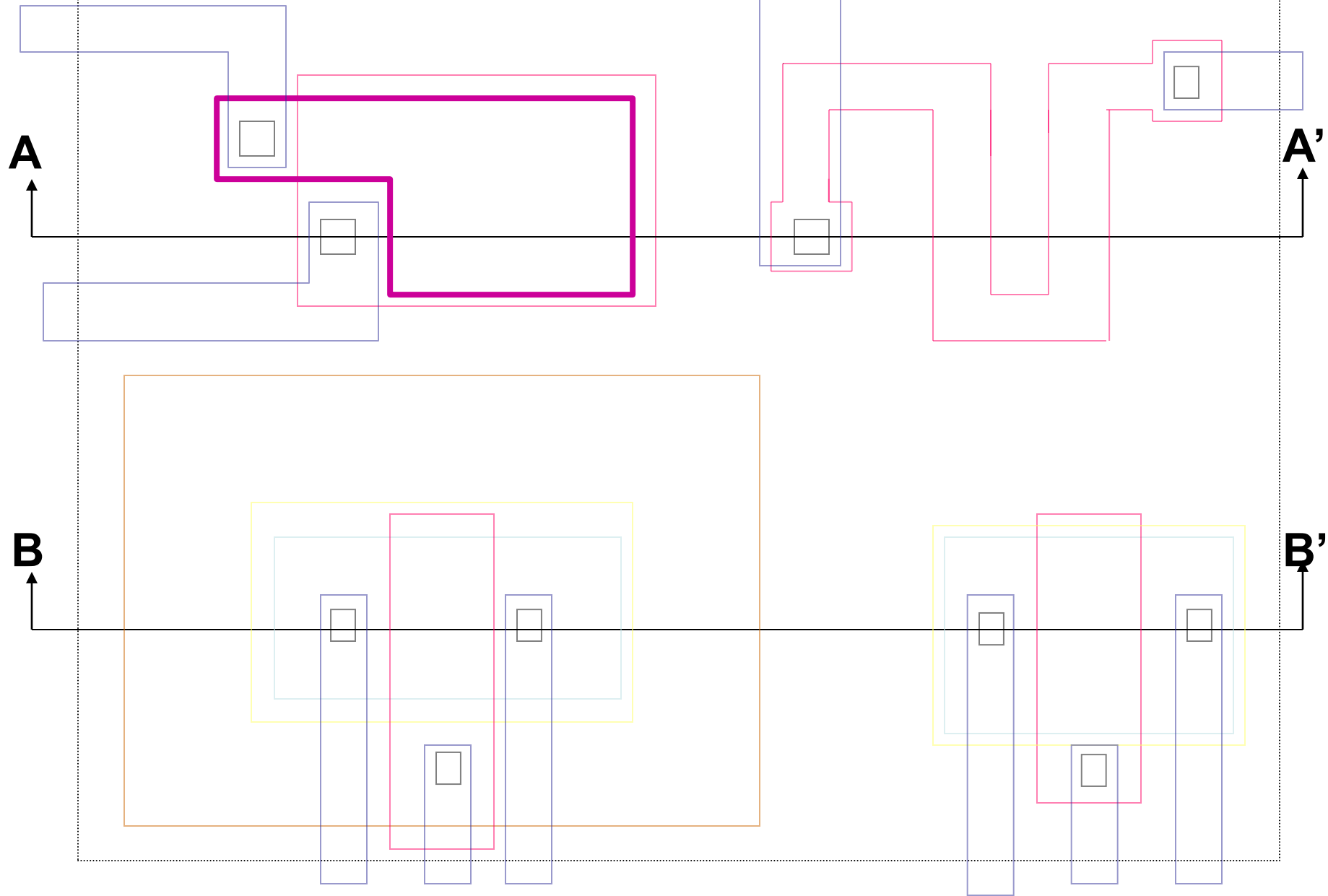
25. Strip photoresist
Optional steps for double polysilicon process
 - B.1 Strip thin oxide
 - B.2 GROW THIN OXIDE
 - B.3 POLYSILICON DEPOSITION (POLY II)
 - B.4 Apply photoresist
 - B.5 PATTERN POLYSILICON
 - B.6 Develop photoresist
 - B.7 ETCH POLYSILICON
 - B.8 Strip photoresist
 - B.9 Strip thin oxide

26. Apply photoresist
27. PATTERN P-CHANNEL DRAINS AND SOURCES AND P⁺ GUARD RINGS (p-well ohmic contacts) (MASK #4)
28. Develop photoresist
29. p⁺ IMPLANT
30. Strip photoresist
31. Apply photoresist
32. PATTERN N-CHANNEL DRAINS AND SOURCES AND N⁺ GUARD RINGS (top ohmic contact to substrate) (MASK #5)
33. Develop photoresist
34. n⁺ IMPLANT
35. Strip photoresist
36. Strip thin oxide
37. Grow oxide
38. Apply photoresist
39. PATTERN CONTACT OPENINGS (MASK #6)
40. Develop photoresist
41. Etch oxide
42. Strip photoresist

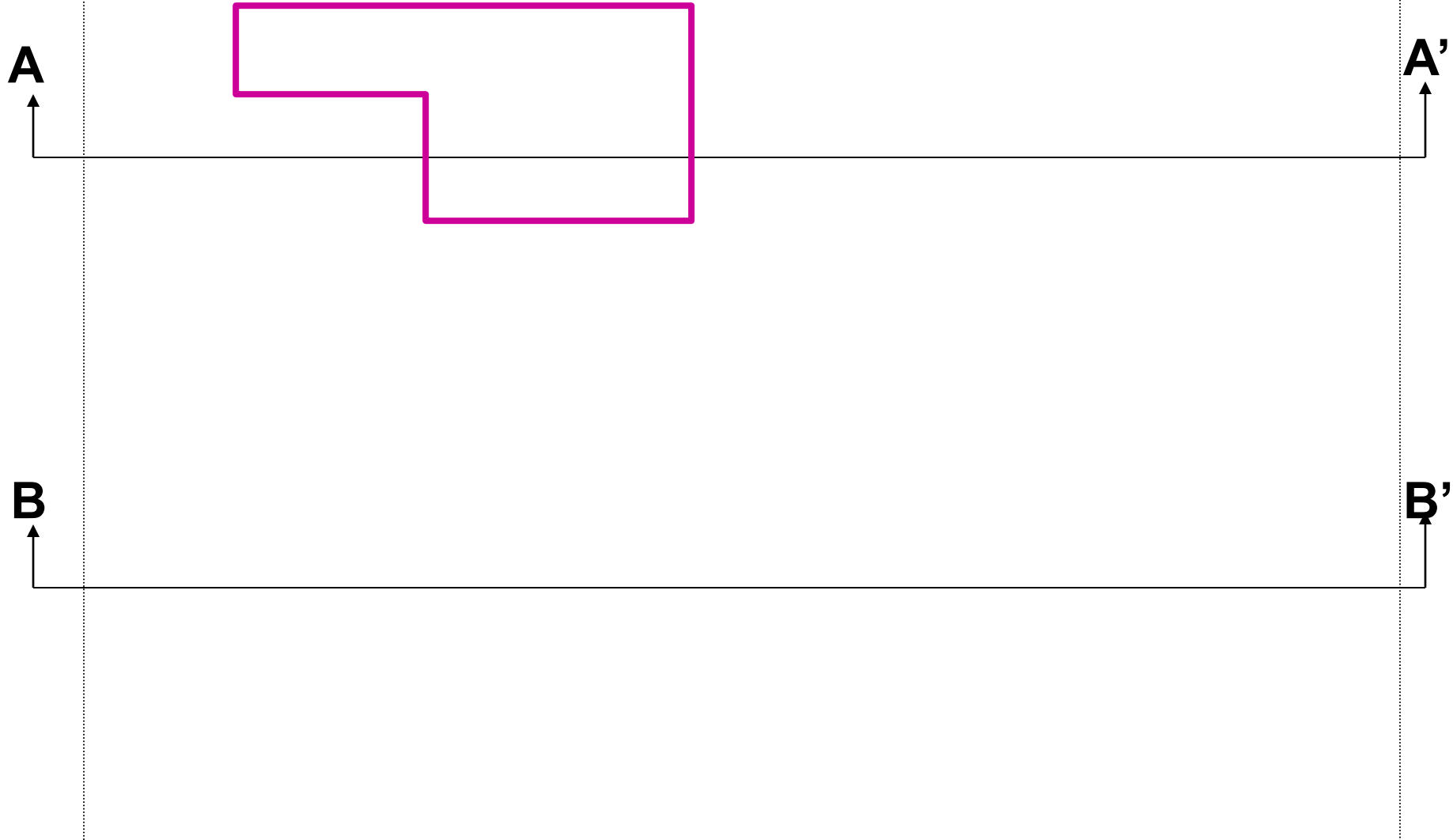


Poly II mask

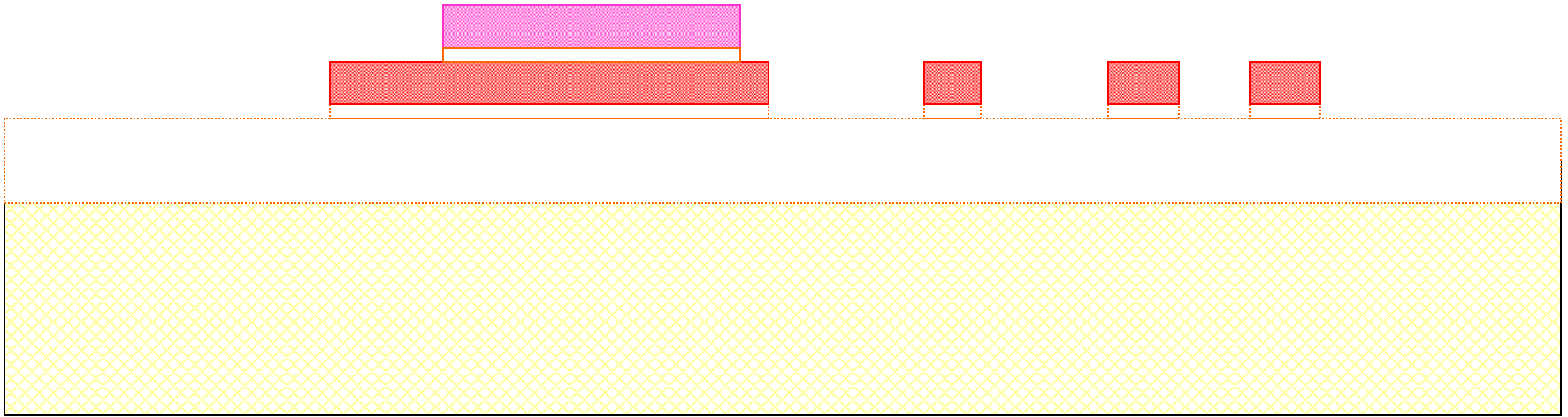
Poly 2 Mask



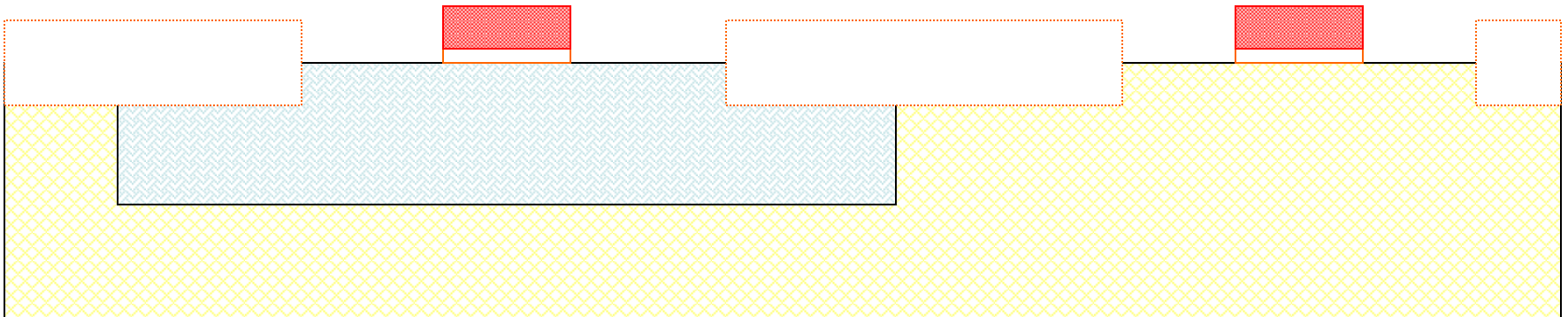
Poly 2 Mask



Poly 2 Mask



A-A' Section



B-B' Section

TABLE 2B.1

Process scenario of major process steps in typical n-well CMOS process^a

- | | | |
|-----|---|------------|
| 1. | Clean wafer | |
| 2. | GROW THIN OXIDE | |
| 3. | Apply photoresist | |
| 4. | PATTERN n-well | (MASK #1) |
| 5. | Develop photoresist | |
| 6. | Deposit and diffus n-type impurities | |
| 7. | Strip photoresist | |
| 8. | Strip thin oxide | |
| 9. | Grow thin oxide | |
| 10. | Apply layer of Si ₃ N ₄ | |
| 11. | Apply photoresist | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) |
| 13. | Develop photoresist | |
| 14. | Etch Si ₃ N ₄ | |
| 15. | Strip photoresist | |
| | <i>Optional field threshold voltage adjust</i> | |
| | A.1 Apply photoresist | |
| | A.2 PATTERN ANTIMONATE IN SUBSTRATE | (MASK #A1) |
| | A.3 Develop photoresist | |
| | A.4 FIELD IMPLANT (p-type) | |
| | A.5 Strip photoresist | |
| 16. | GROW FIELD OXIDE | |
| 17. | Strip Si ₃ N ₄ | |
| 18. | Strip thin oxide | |
| 19. | GROW GATE OXIDE | |
| 20. | POLYSILICON DEPOSITION (POLY I) | |
| 21. | Apply photoresist | |
| 22. | PATTERN POLYSILICON | (MASK #3) |
| 23. | Develop photoresist | |
| 24. | ETCH POLYSILICON | |

- 25. Strip photoresist
Optional steps for double polysilicon process
 - B.1 Strip thin oxide
 - B.2 GROW THIN OXIDE
 - B.3 POLYSILICON DEPOSITION (POLY II)
 - B.4 Apply photoresist
 - B.5 PATTERN POLYSILICON
 - B.6 Develop photoresist
 - B.7 ETCH POLYSILICON
 - B.8 Strip photoresist
 - B.9 Strip thin oxide

(MASK #B1)

Poly II mask

- 26. Apply photoresist
- 27. PATTERN P-CHANNEL DRAINS AND SOURCES AND P⁺ GUARD RINGS (p-well ohmic contacts)
- 28. Develop photoresist
- 29. p⁺ IMPLANT
- 30. Strip photoresist
- 31. Apply photoresist
- 32. PATTERN N-CHANNEL DRAINS AND SOURCES AND N⁺ GUARD RINGS (top ohmic contact to substrate)
- 33. Develop photoresist
- 34. n⁺ IMPLANT
- 35. Strip photoresist
- 36. Strip thin oxide
- 37. Grow oxide
- 38. Apply photoresist
- 39. PATTERN CONTACT OPENINGS
- 40. Develop photoresist
- 41. Etch oxide
- 42. Strip photoresist

(MASK #4)

p-select mask

(MASK #5)

n-select mask

(MASK #6)

P-Select

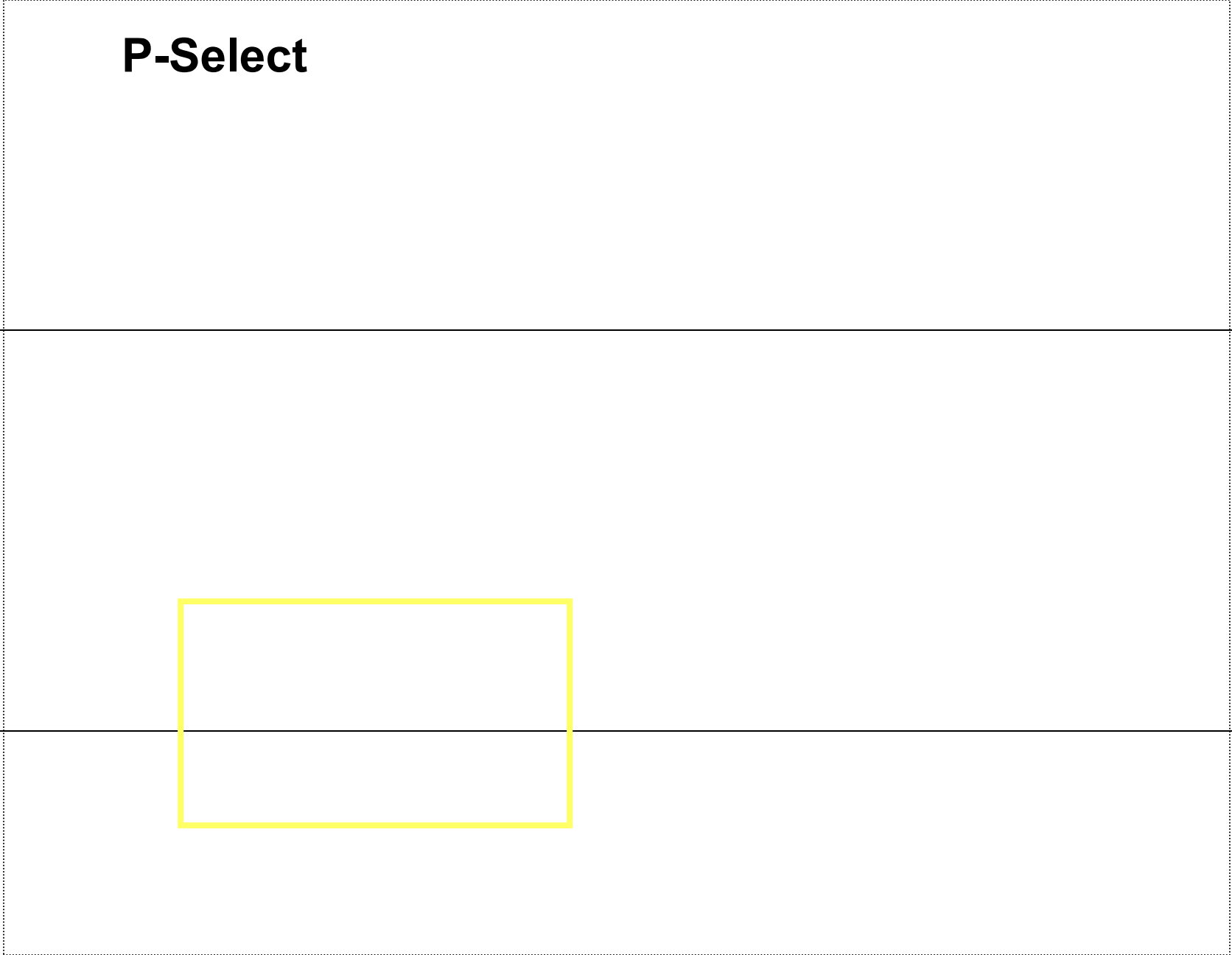
A

A'

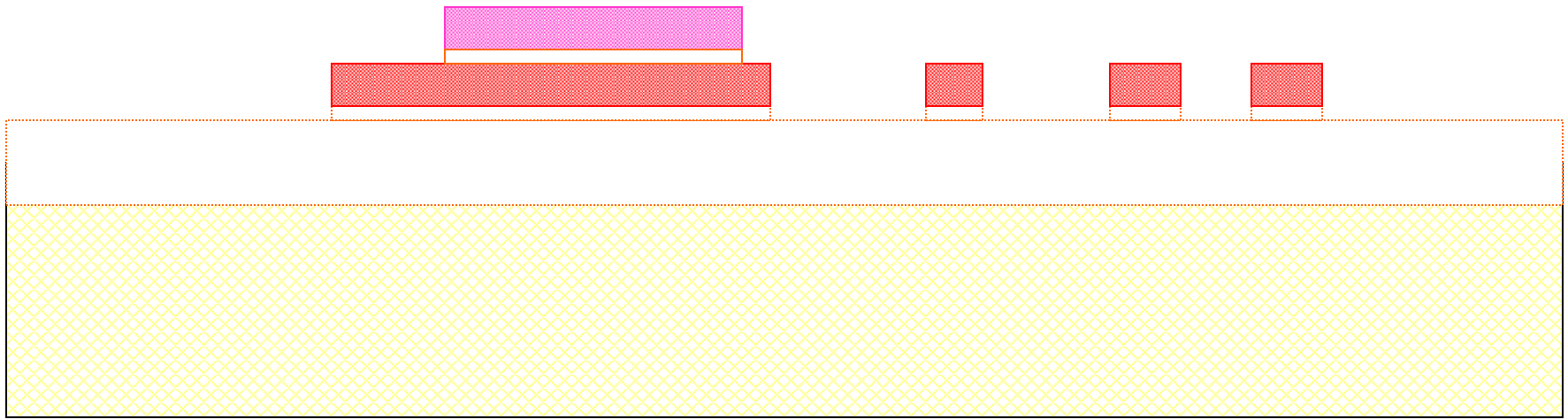


B

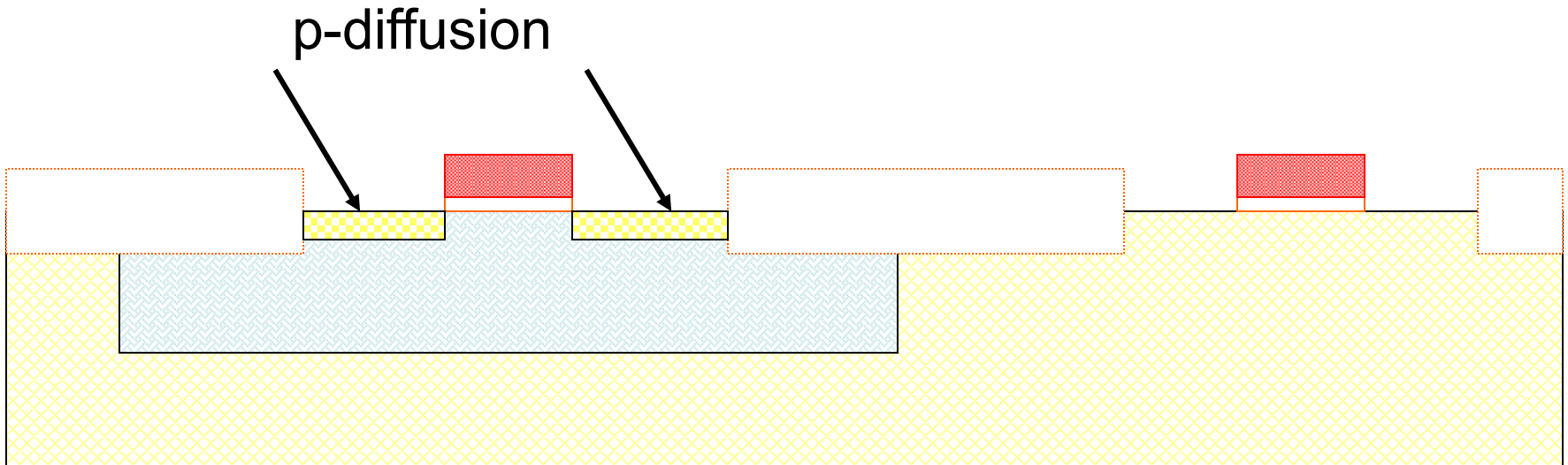
B'



P-Select Mask – p-diffusion



A-A' Section

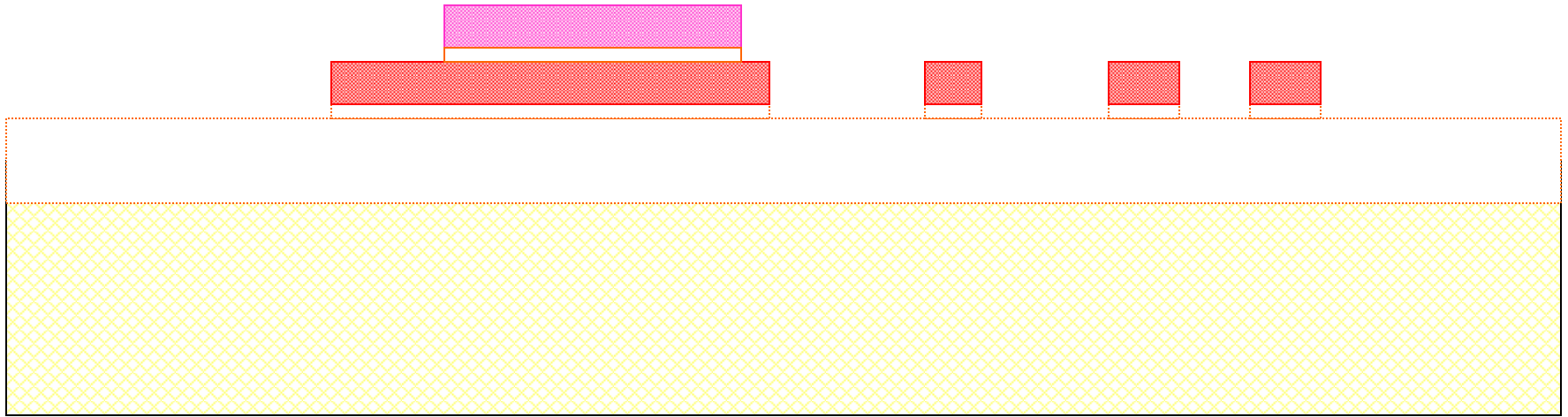


Note the gate is self aligned !!

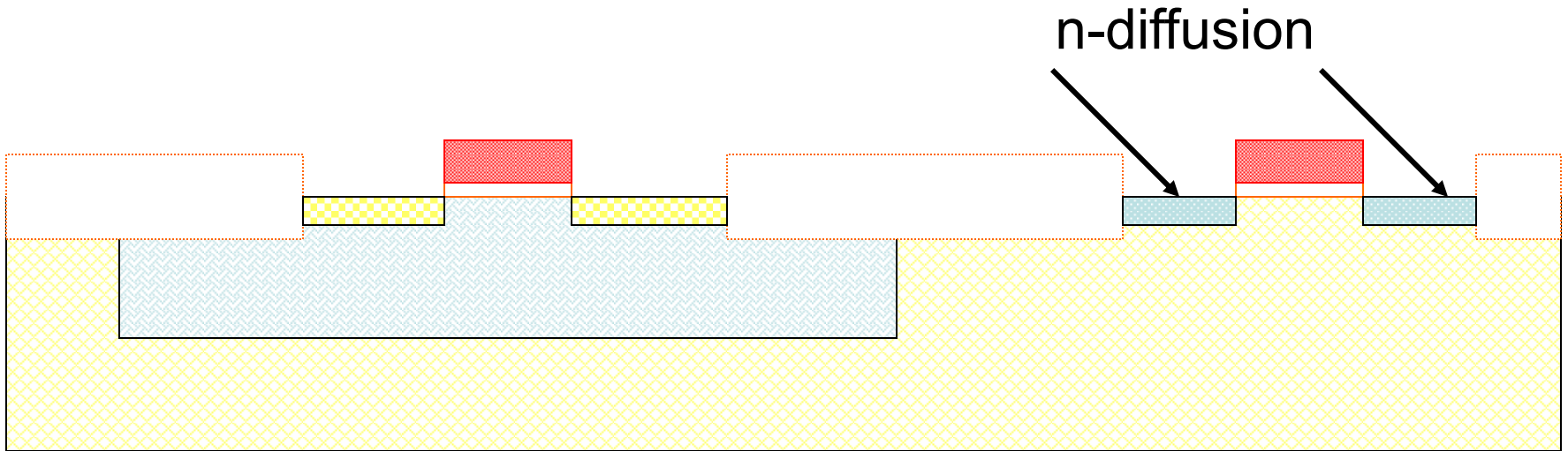
B-B' Section

Note $C_{OXn} = C_{OXp}$!!

n-Select Mask – n-diffusion



A-A' Section



B-B' Section

TABLE 2B.1

Process scenario of major process steps in typical n-well CMOS process^a

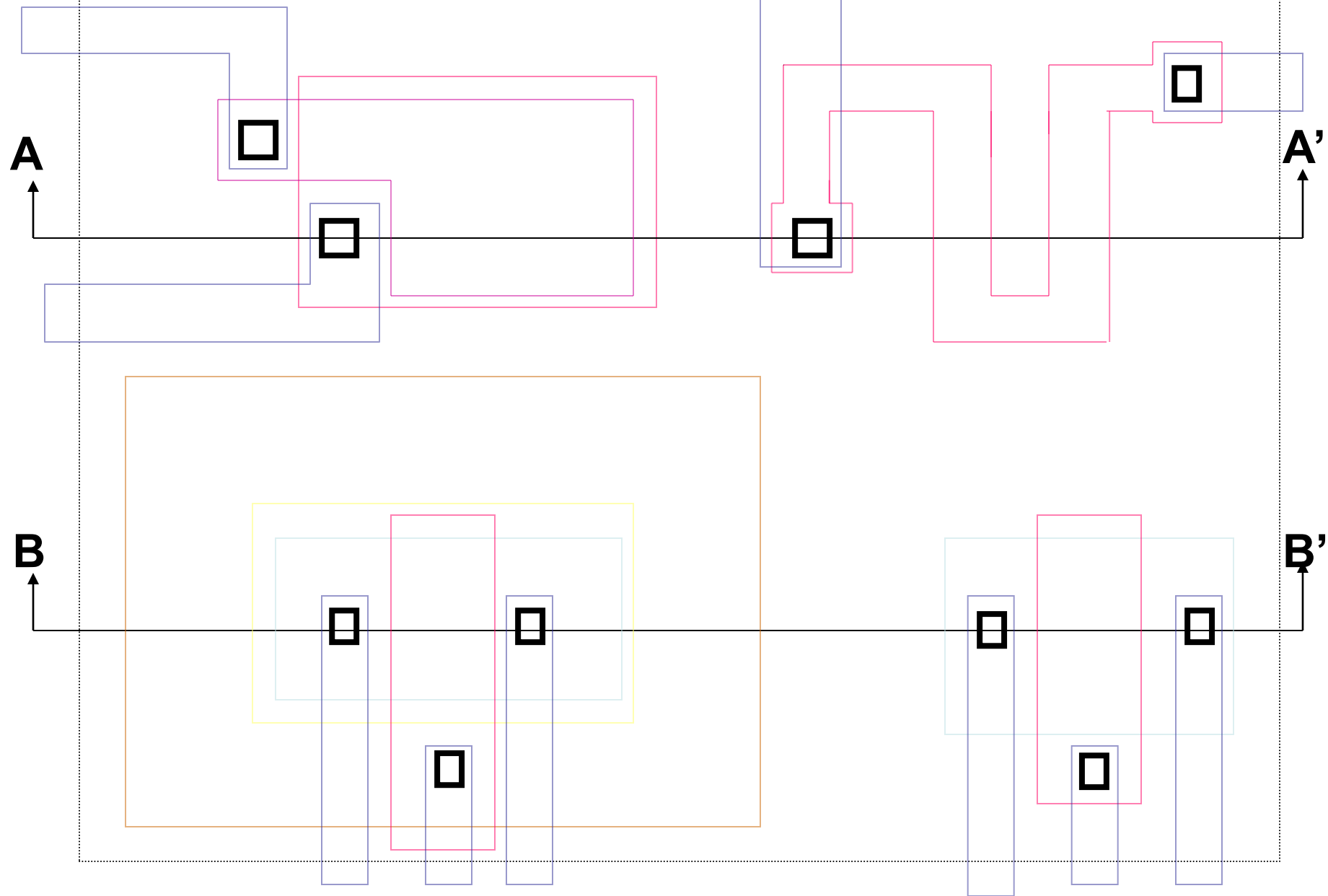
- | | | |
|-----|---|------------|
| 1. | Clean wafer | |
| 2. | GROW THIN OXIDE | |
| 3. | Apply photoresist | |
| 4. | PATTERN n-well | (MASK #1) |
| 5. | Develop photoresist | |
| 6. | Deposit and diffus n-type impurities | |
| 7. | Strip photoresist | |
| 8. | Strip thin oxide | |
| 9. | Grow thin oxide | |
| 10. | Apply layer of Si ₃ N ₄ | |
| 11. | Apply photoresist | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) |
| 13. | Develop photoresist | |
| 14. | Etch Si ₃ N ₄ | |
| 15. | Strip photoresist | |
| | <i>Optional field threshold voltage adjust</i> | |
| | A.1 Apply photoresist | |
| | A.2 PATTERN ANTIMONATE IN SUBSTRATE | (MASK #A1) |
| | A.3 Develop photoresist | |
| | A.4 FIELD IMPLANT (p-type) | |
| | A.5 Strip photoresist | |
| 16. | GROW FIELD OXIDE | |
| 17. | Strip Si ₃ N ₄ | |
| 18. | Strip thin oxide | |
| 19. | GROW GATE OXIDE | |
| 20. | POLYSILICON DEPOSITION (POLY I) | |
| 21. | Apply photoresist | |
| 22. | PATTERN POLYSILICON | (MASK #3) |
| 23. | Develop photoresist | |
| 24. | ETCH POLYSILICON | |

- | | | | |
|-----|--|------------|---------------|
| 25. | Strip photoresist <i>Optional steps for double polysilicon process</i> B.1 Strip thin oxide B.2 GROW THIN OXIDE B.3 POLYSILICON DEPOSITION (POLY II) B.4 Apply photoresist B.5 PATTERN POLYSILICON B.6 Develop photoresist B.7 ETCH POLYSILICON B.8 Strip photoresist B.9 Strip thin oxide | (MASK #B1) | Poly II mask |
| 26. | Apply photoresist | | |
| 27. | PATTERN P-CHANNEL DRAINS AND SOURCES AND P ⁺ GUARD RINGS (p-well ohmic contacts) | (MASK #4) | p-select mask |
| 28. | Develop photoresist | | |
| 29. | p ⁺ IMPLANT | | |
| 30. | Strip photoresist | | |
| 31. | Apply photoresist | | |
| 32. | PATTERN N-CHANNEL DRAINS AND SOURCES AND N ⁺ GUARD RINGS (top ohmic contact to substrate) | (MASK #5) | n-select mask |
| 33. | Develop photoresist | | |
| 34. | n ⁺ IMPLANT | | |
| 35. | Strip photoresist | | |
| 36. | Strip thin oxide | | |
| 37. | Grow oxide | | |
| 38. | Apply photoresist | | |
| 39. | PATTERN CONTACT OPENINGS | (MASK #6) | contact mask |
| 40. | Develop photoresist | | |
| 41. | Etch oxide | | |
| 42. | Strip photoresist | | |

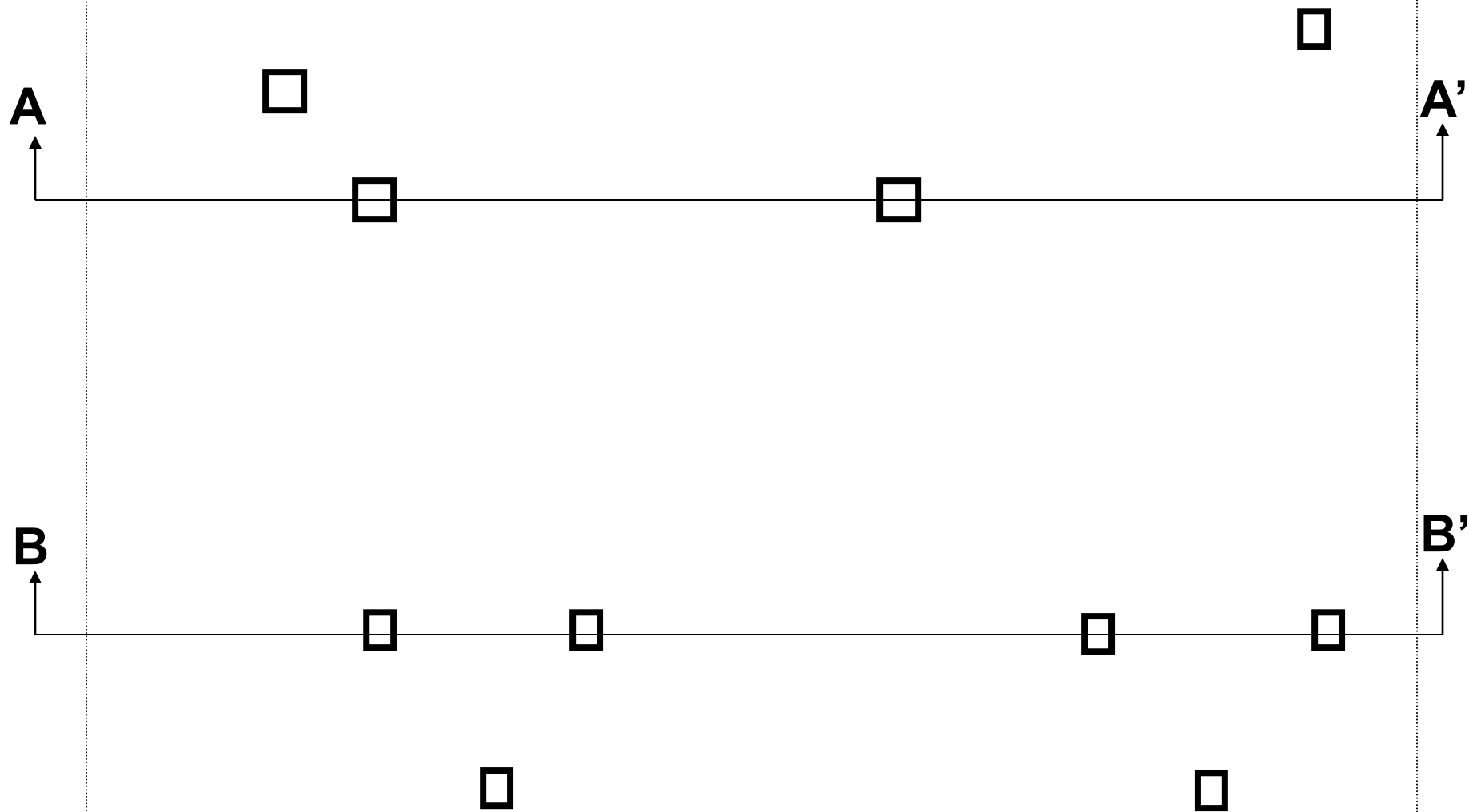


43. APPLY METAL
44. Apply photoresist
45. PATTERN METAL (MASK #7)
46. Develop photoresist
47. Etch metal
48. Strip photoresist
Optional steps for double metal process
 - C.1 Strip thin oxide
 - C.2 DEPOSIT INTERMETAL OXIDE
 - C.3 Apply photoresist
 - C.4 PATTERN VIAS (MASK #C1)
 - C.5 Develop photoresist
 - C.6 Etch oxide
 - C.7 Strip photoresist
 - C.8 APPLY METAL (Metal 2)
 - C.9 Apply photoresist
 - C.10 PATTERN METAL (MASK #C2)
 - C.11 Develop photoresist
 - C.12 Etch metal
 - C.13 Strip photoresist
49. APPLY PASSIVATION
50. Apply photoresist
51. PATTERN PAD OPENINGS (MASK #8)
52. Develop photoresist
53. Etch passivation
54. Strip photoresist
55. ASSEMBLE, PACKAGE AND TEST

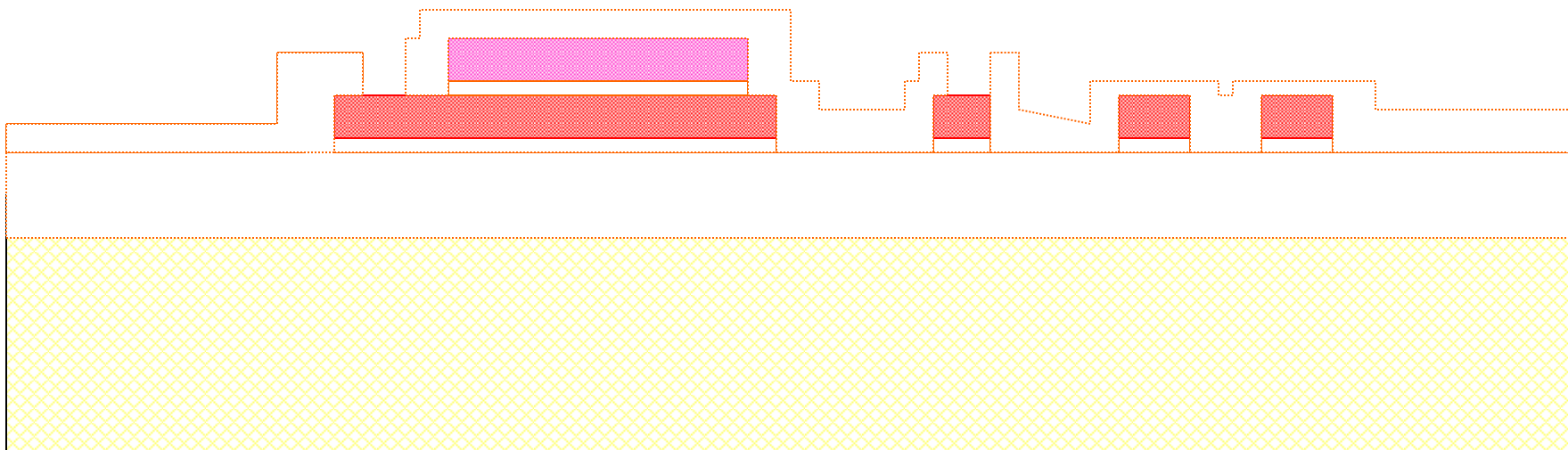
Contact Mask



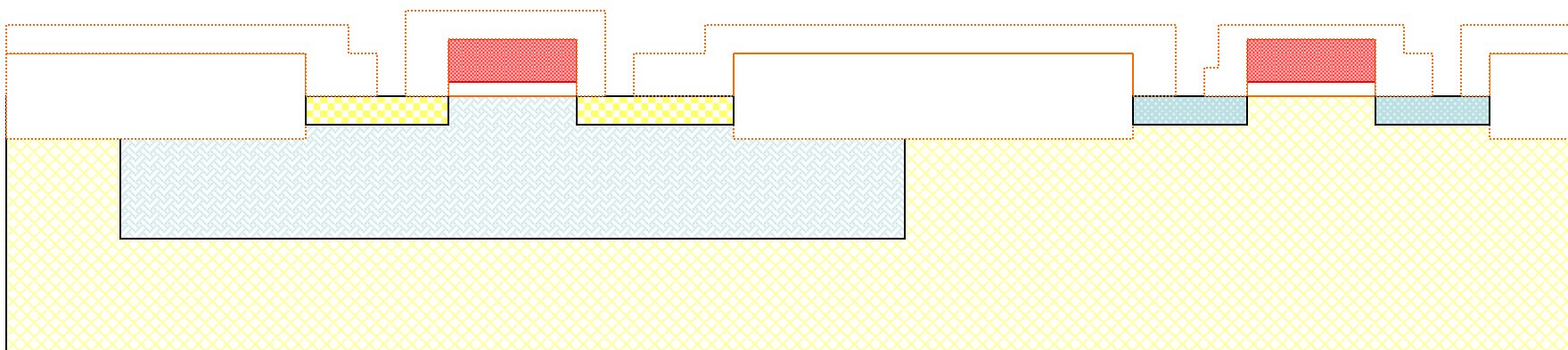
Contact Mask



Contact Mask



A-A' Section



B-B' Section

TABLE 2B.1

Process scenario of major process steps in typical n-well CMOS process^a

- | | | |
|-----|---|------------|
| 1. | Clean wafer | |
| 2. | GROW THIN OXIDE | |
| 3. | Apply photoresist | |
| 4. | PATTERN n-well | (MASK #1) |
| 5. | Develop photoresist | |
| 6. | Deposit and diffus n-type impurities | |
| 7. | Strip photoresist | |
| 8. | Strip thin oxide | |
| 9. | Grow thin oxide | |
| 10. | Apply layer of Si ₃ N ₄ | |
| 11. | Apply photoresist | |
| 12. | PATTERN Si ₃ N ₄ (active area definition) | (MASK #2) |
| 13. | Develop photoresist | |
| 14. | Etch Si ₃ N ₄ | |
| 15. | Strip photoresist | |
| | <i>Optional field threshold voltage adjust</i> | |
| | A.1 Apply photoresist | |
| | A.2 PATTERN ANTIMOAT IN SUBSTRATE | (MASK #A1) |
| | A.3 Develop photoresist | |
| | A.4 FIELD IMPLANT (p-type) | |
| | A.5 Strip photoresist | |
| 16. | GROW FIELD OXIDE | |
| 17. | Strip Si ₃ N ₄ | |
| 18. | Strip thin oxide | |
| 19. | GROW GATE OXIDE | |
| 20. | POLYSILICON DEPOSITION (POLY I) | |
| 21. | Apply photoresist | |
| 22. | PATTERN POLYSILICON | (MASK #3) |
| 23. | Develop photoresist | |
| 24. | ETCH POLYSILICON | |

25. Strip photoresist
Optional steps for double polysilicon process
 - B.1 Strip thin oxide
 - B.2 GROW THIN OXIDE
 - B.3 POLYSILICON DEPOSITION (POLY II)
 - B.4 Apply photoresist
 - B.5 PATTERN POLYSILICON (MASK #B1)
 - B.6 Develop photoresist
 - B.7 ETCH POLYSILICON
 - B.8 Strip photoresist
 - B.9 Strip thin oxide

26. Apply photoresist
27. PATTERN P-CHANNEL DRAINS AND SOURCES AND P⁺ GUARD RINGS (p-well ohmic contacts) (MASK #4)
28. Develop photoresist
29. p⁺ IMPLANT
30. Strip photoresist
31. Apply photoresist
32. PATTERN N-CHANNEL DRAINS AND SOURCES AND N⁺ GUARD RINGS (top ohmic contact to substrate) (MASK #5)
33. Develop photoresist
34. n⁺ IMPLANT
35. Strip photoresist
36. Strip thin oxide
37. Grow oxide
38. Apply photoresist
39. PATTERN CONTACT OPENINGS (MASK #6)
40. Develop photoresist
41. Etch oxide
42. Strip photoresist



- 43. APPLY METAL
- 44. Apply photoresist
- 45. PATTERN METAL
- 46. Develop photoresist
- 47. Etch metal
- 48. Strip photoresist
- Optional steps for double metal process*
- C.1 Strip thin oxide
- C.2 DEPOSIT INTERMETAL OXIDE
- C.3 Apply photoresist
- C.4 PATTERN VIAS
- C.5 Develop photoresist
- C.6 Etch oxide
- C.7 Strip photoresist
- C.8 APPLY METAL (Metal 2)
- C.9 Apply photoresist
- C.10 PATTERN METAL
- C.11 Develop photoresist
- C.12 Etch metal
- C.13 Strip photoresist
- 49. APPLY PASSIVATION
- 50. Apply photoresist
- 51. PATTERN PAD OPENINGS
- 52. Develop photoresist
- 53. Etch passivation
- 54. Strip photoresist
- 55. ASSEMBLE, PACKAGE AND TEST



(MASK #7)

Metal 1 mask

(MASK #C1)

Via mask

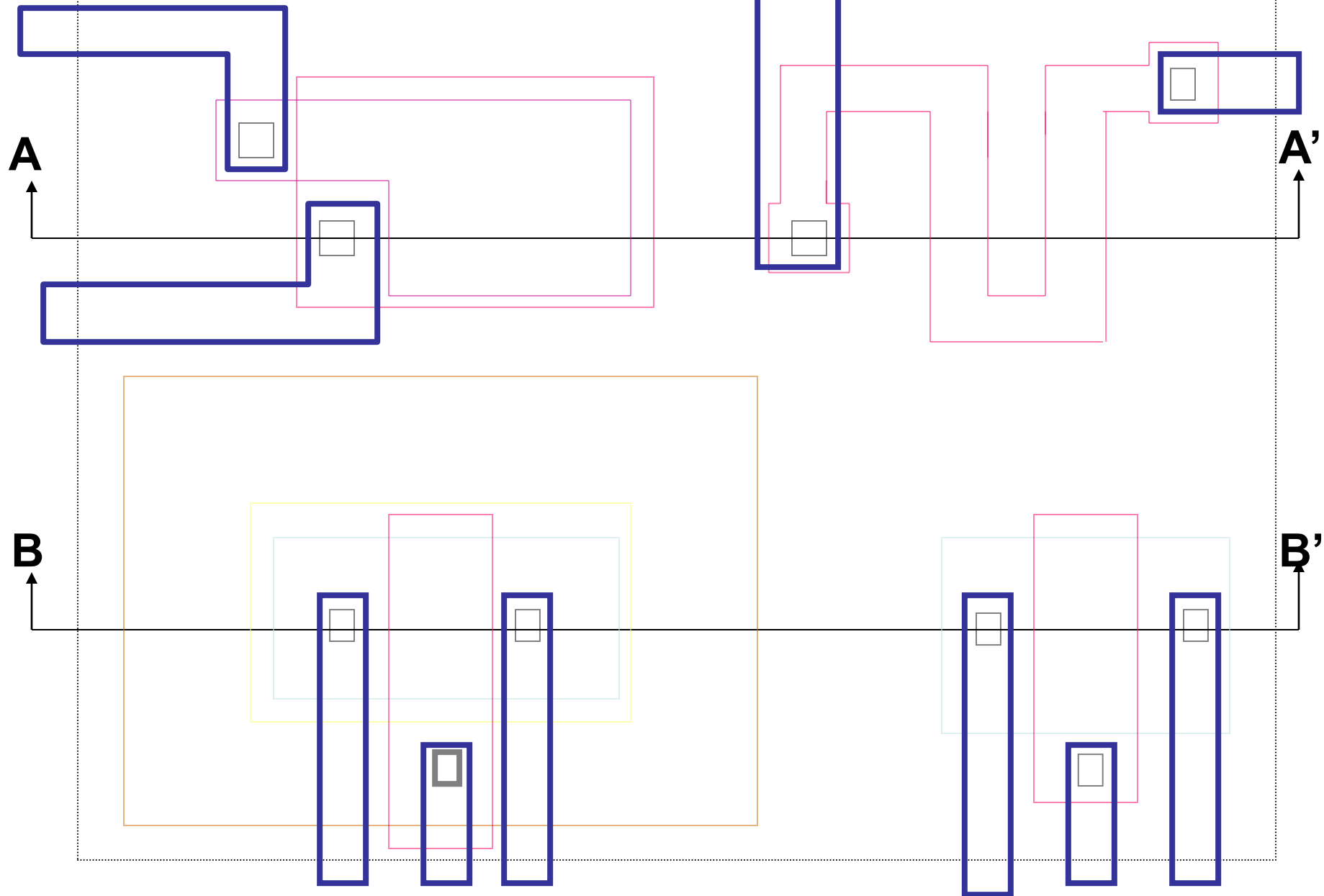
(MASK #C2)

Metal 2 mask

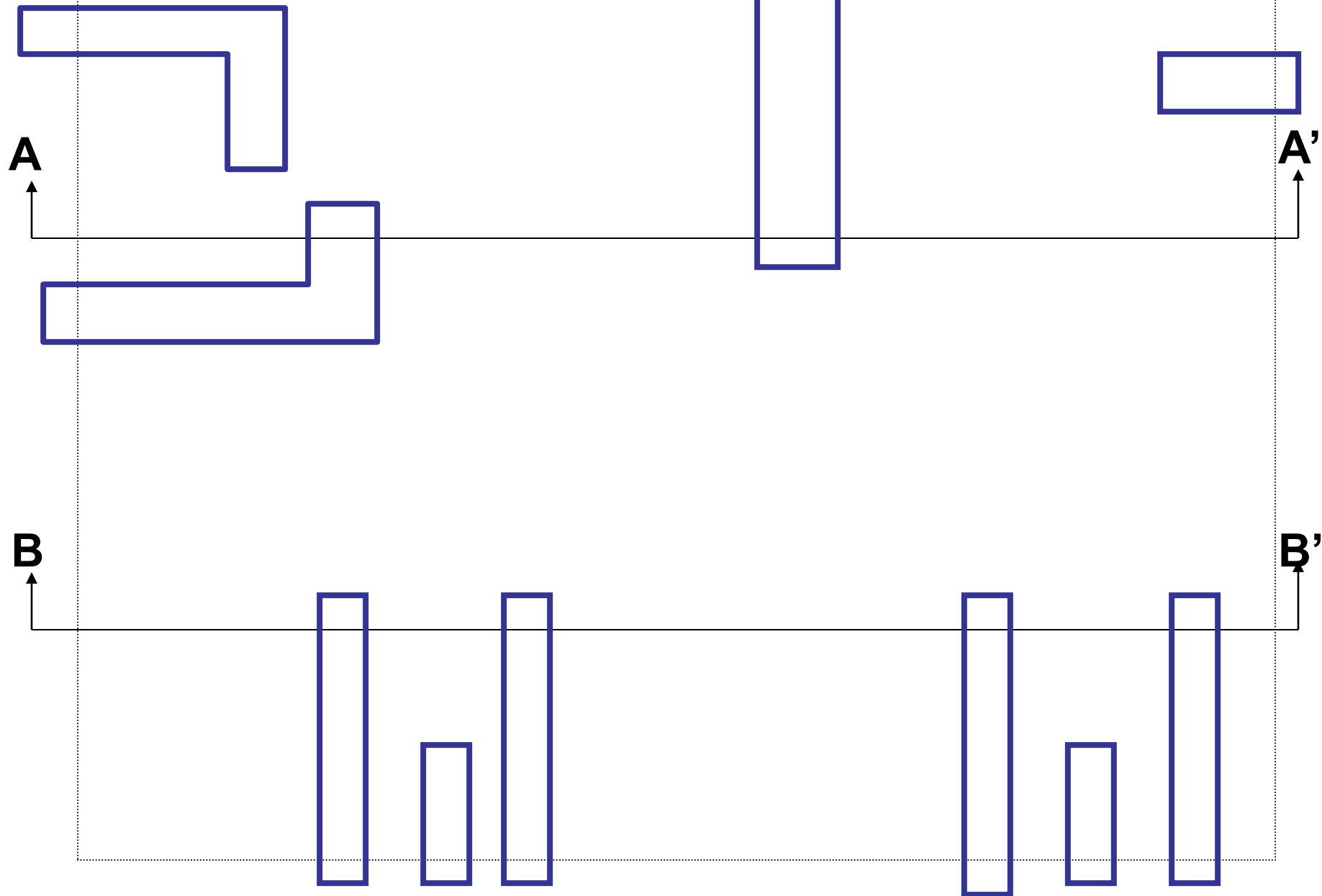
(MASK #8)

Pad Open mask

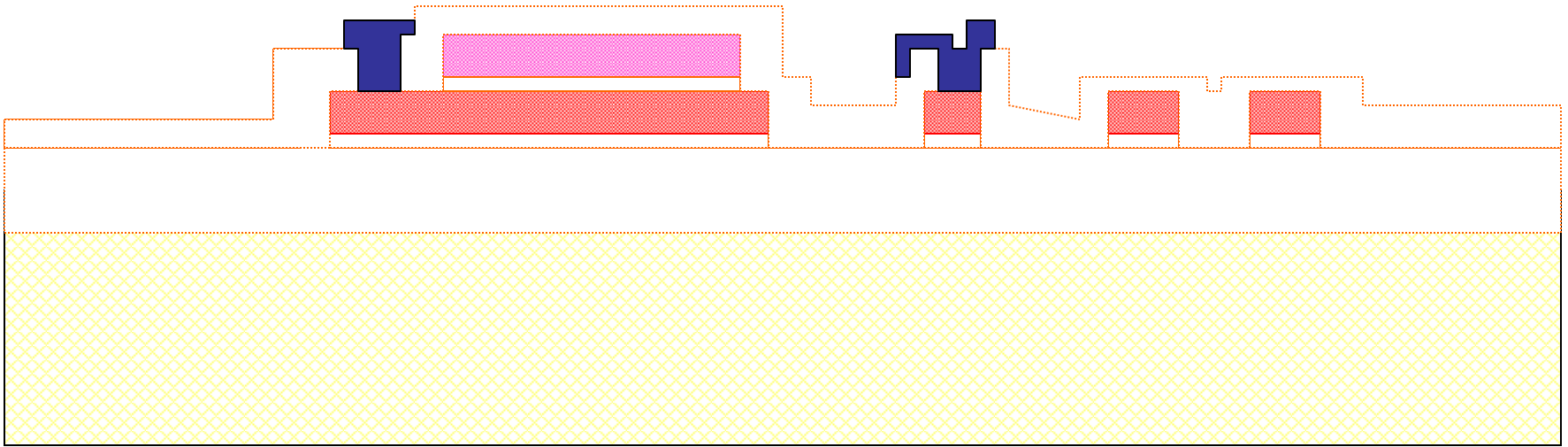
Metal 1 Mask



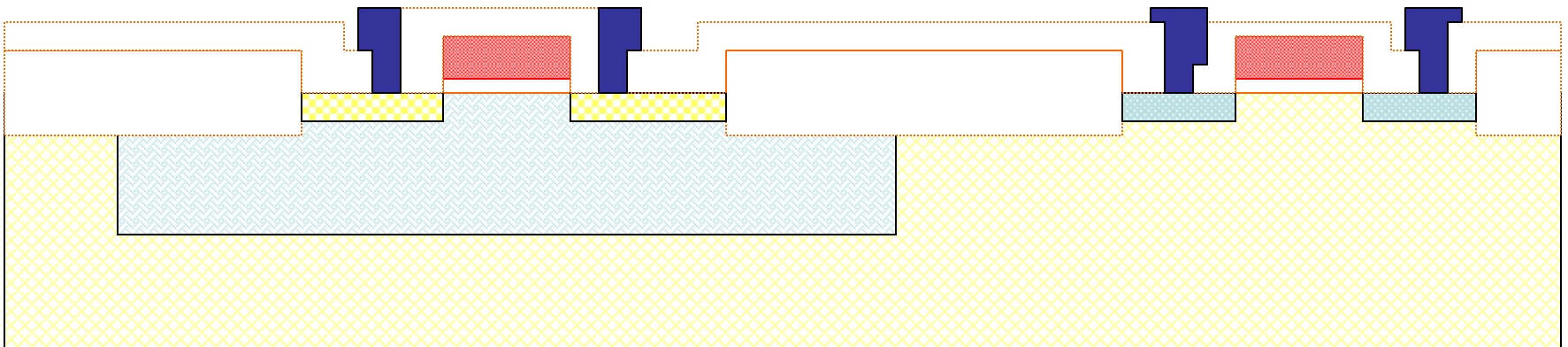
Metal 1 Mask



Metal Mask



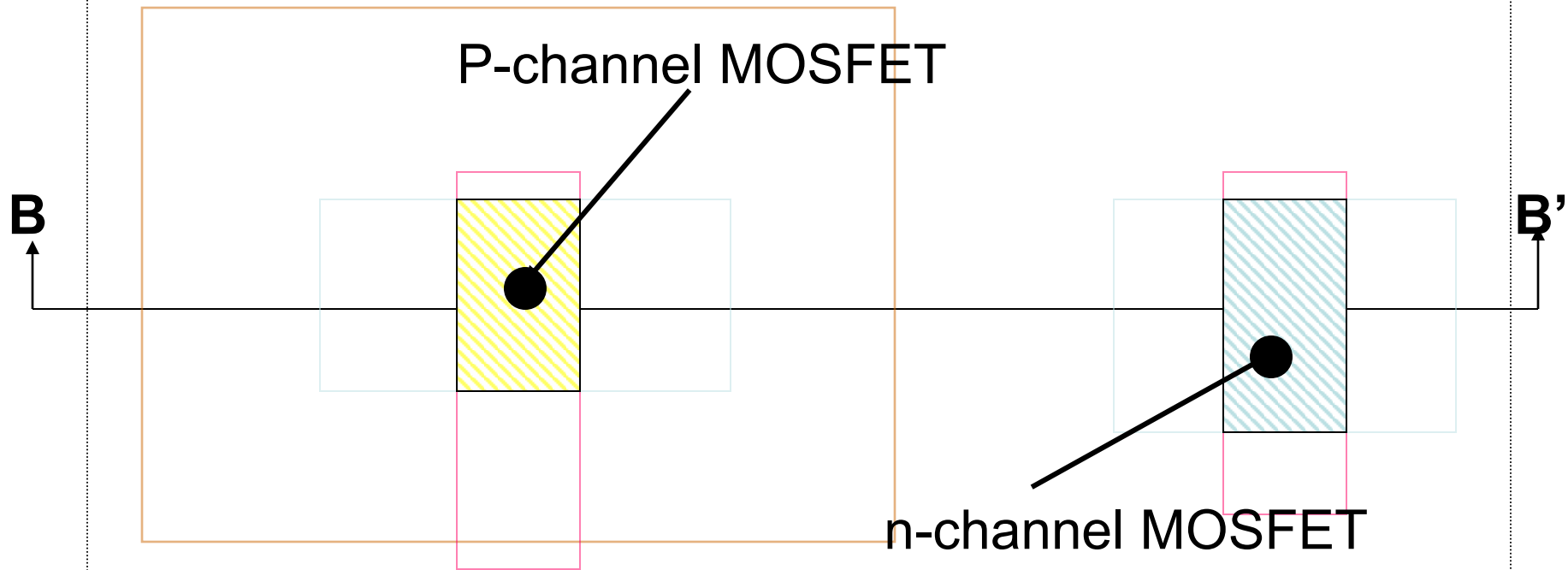
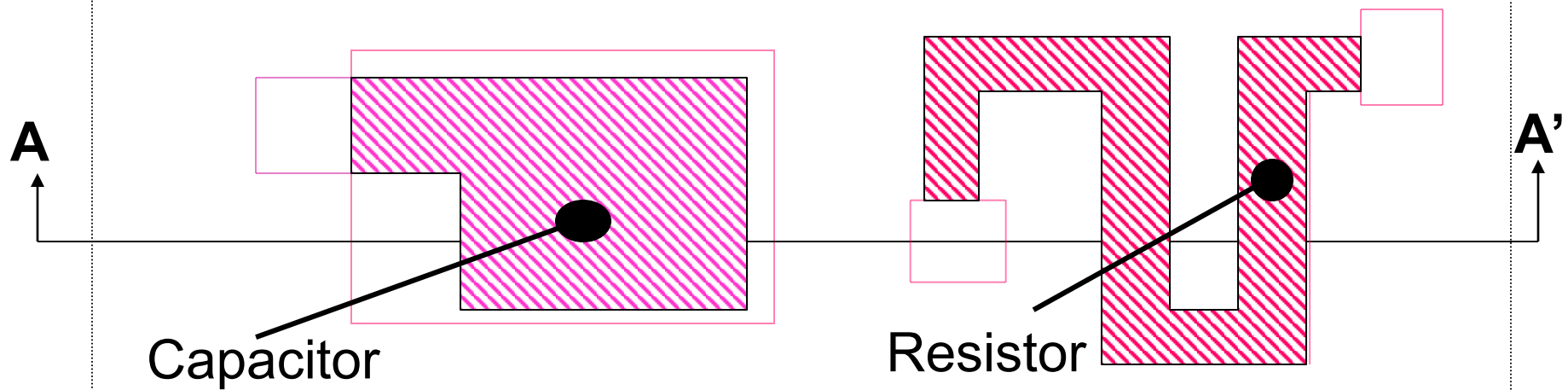
A-A' Section



B-B' Section

Should discuss Metal 2 mask too and mention why we can't go directly from Metal 2 to active

Should also indicate why, on a multi-metal process that we are restricted from going from one level to another only. Else comments later about what can and can't be done don't make any sense.



Should now know what you can do in this process !!

Can metal connect to active?

Can metal connect to substrate when on top of field oxide?

How can metal be connected to substrate?

Can poly be connected to active under gate?

Can poly be connected to active any place?

Can metal be placed under poly to isolate it from bulk?

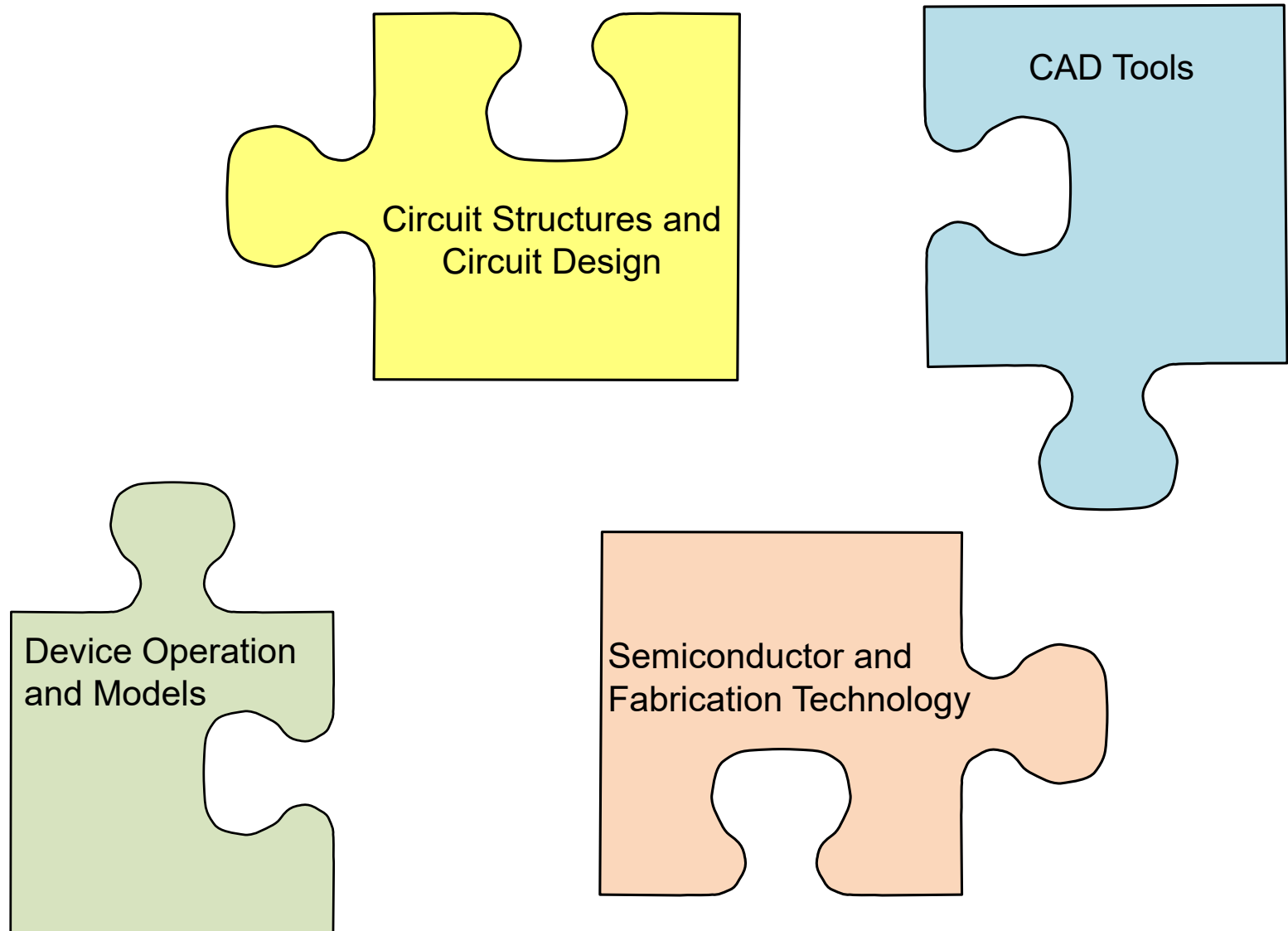
Can metal 2 be connected directly to active?

Can metal 2 be connected to metal 1?

Can metal 2 pass under metal 1?

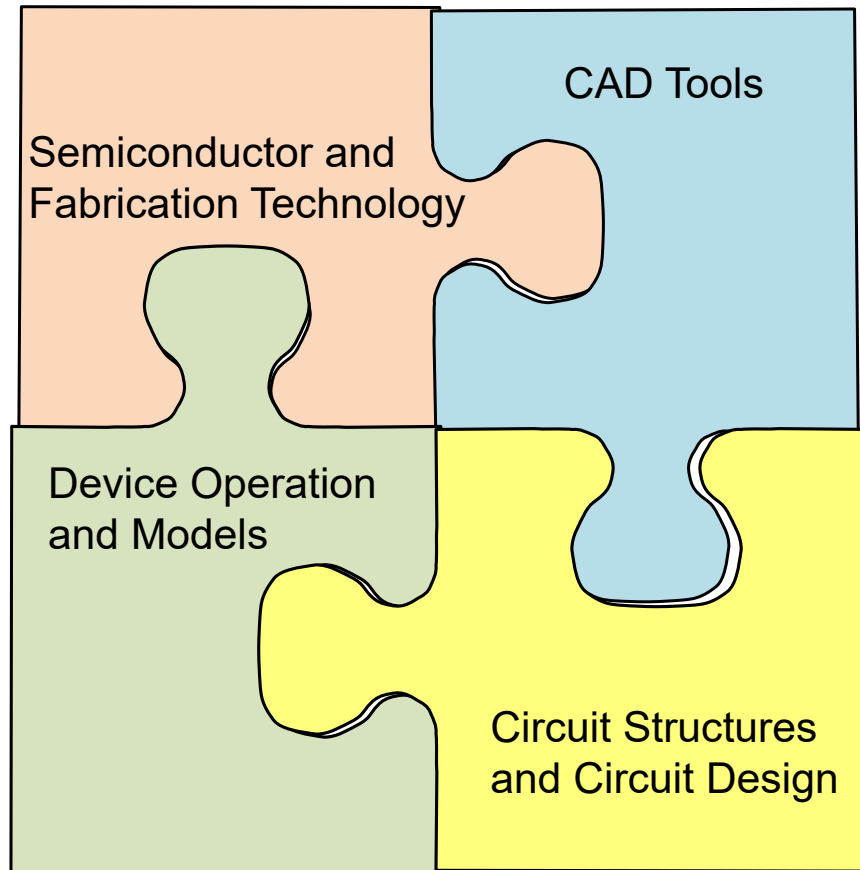
Could a process be created that will result in an answer of YES to most of above?

How we started this course



Thanks for your patience !!

The basic concepts should have now come together





Stay Safe and Stay Healthy !

End of Lecture 18